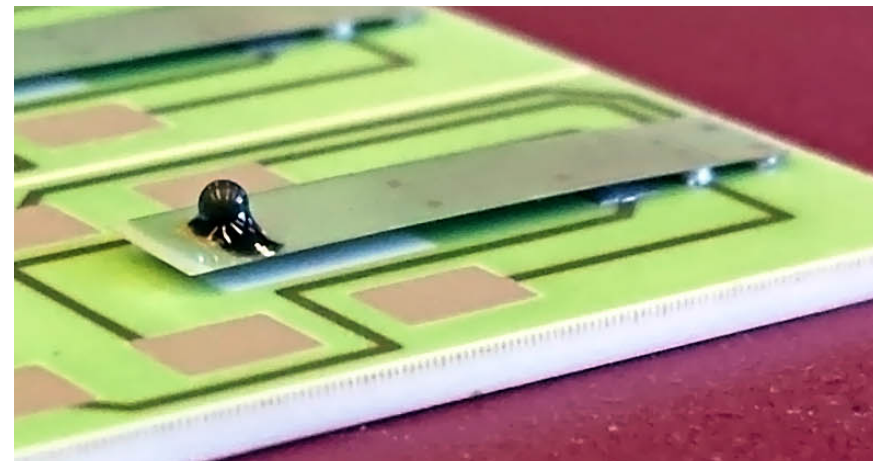
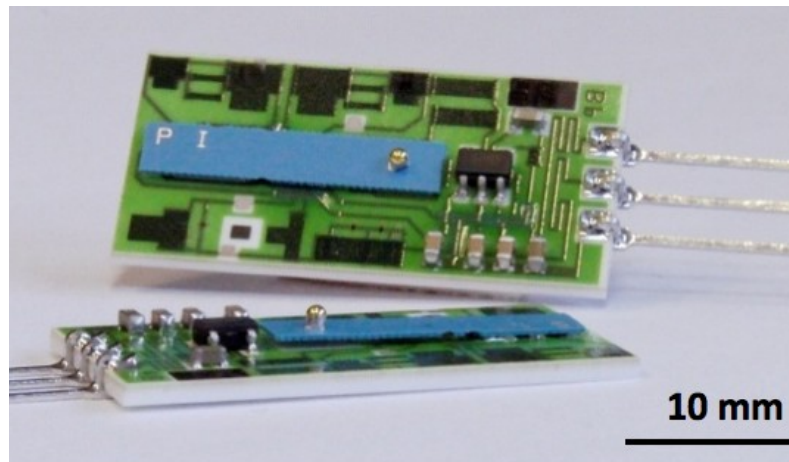


# Fabrication, response and stability of miniature piezoresistive force-sensing thick-film cantilevers

Thomas Maeder, Caroline Jacq, Stefane Caseiro and Peter Ryser  
École Polytechnique Fédérale de Lausanne (EPFL), Switzerland



# Outline

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- 1. Introduction**
- 2. Manufacturing**
- 3. Thermal drift**
- 4. Force response & signal stability**
- 5. Conclusions & outlook**

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# Typical thick-film piezoresistive sensor

## ■ Typical elements

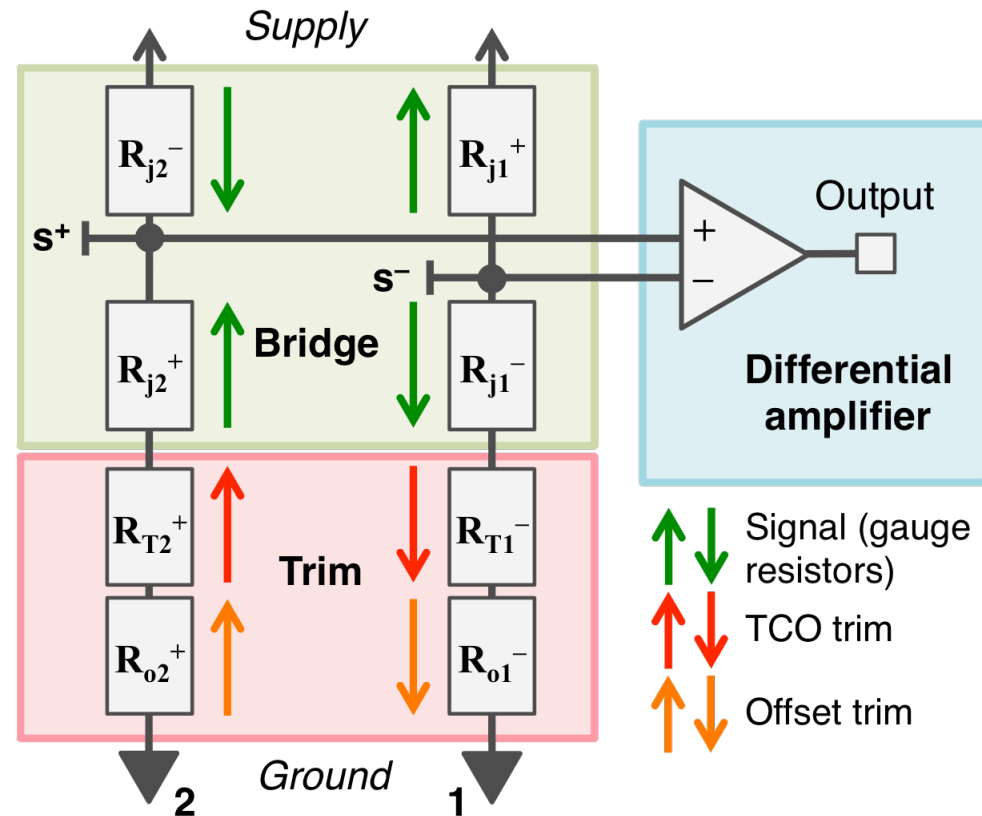
- Sensing bridge
- Offset trim
- TCO trim
- Differential amplifier

## ■ Typical values ( $\pm$ )

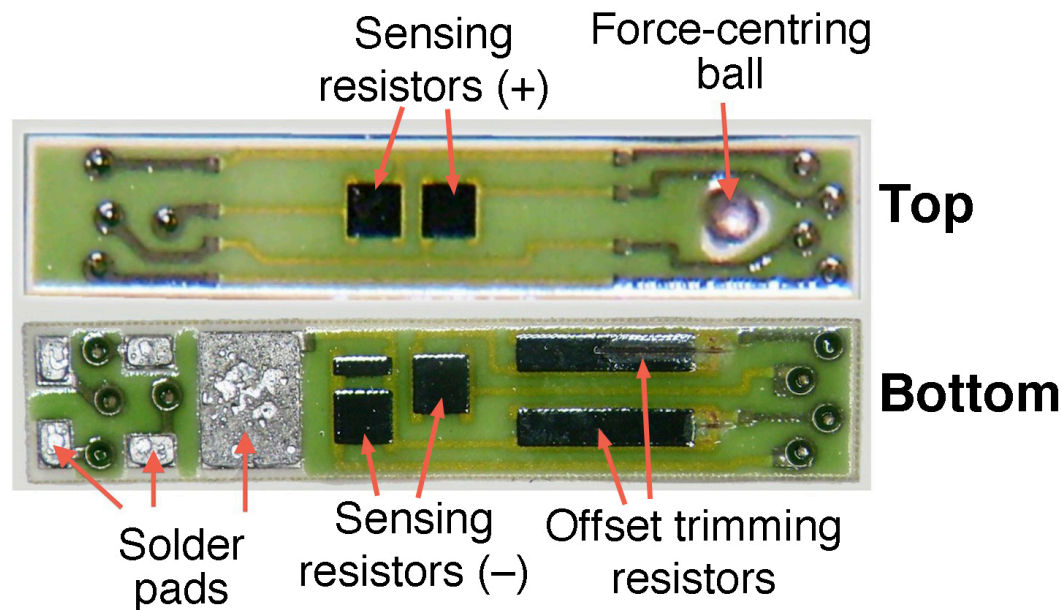
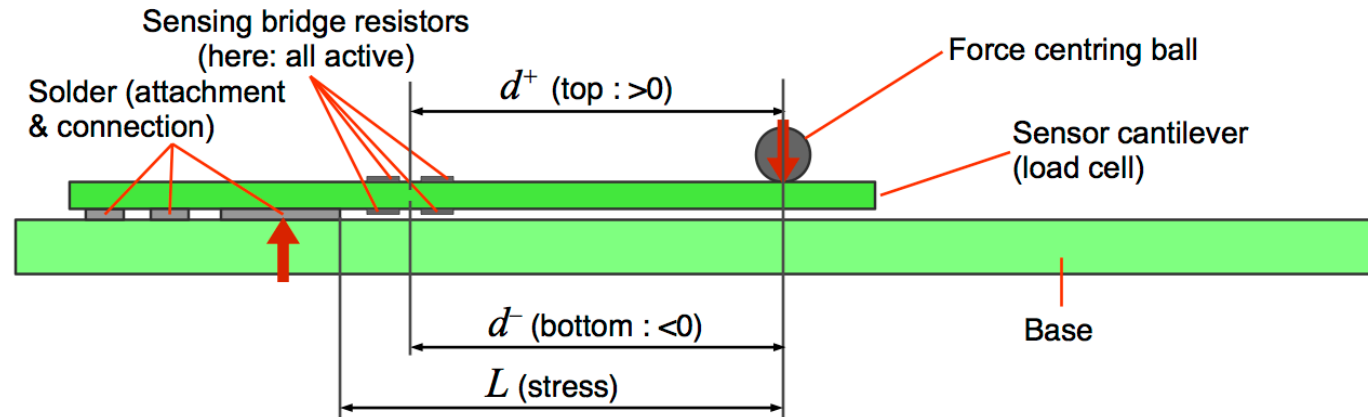
- Offset  $\sim 30$  mV/V
- Response  $\sim 2-3$  mV/V
- TCO  $\sim 1$   $\mu$ V/V/K  
(50 K :  $\sim 0.05$  mV/V,  $\sim 2\%$  F.S.)

## ■ For 0.1% F.S.:

- Offset reduction  $\sim 10'000\times$
- Stability (bridge)  $\sim 2-3$  ppm

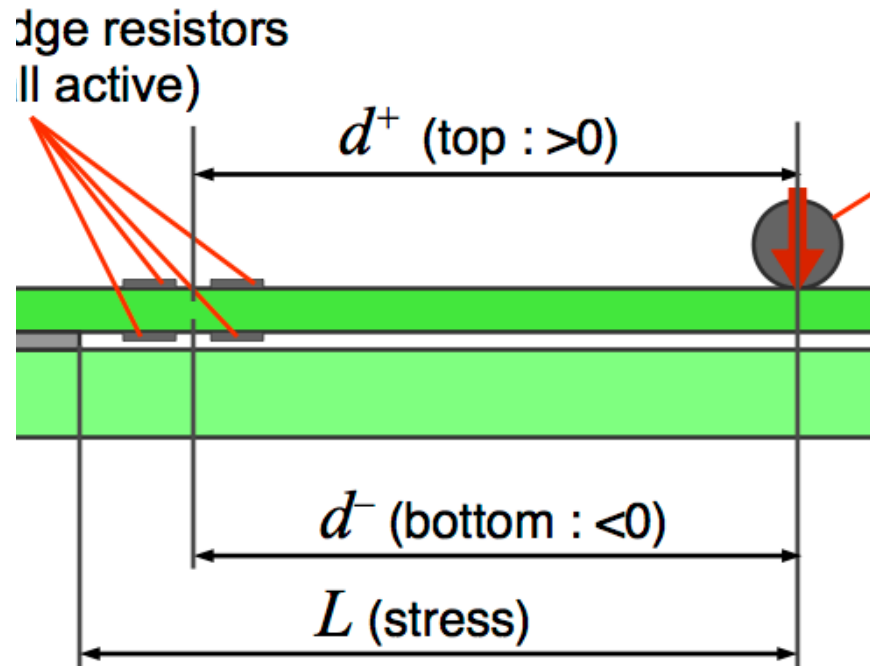


# Cantilever force cell – principle



- Piezoresistive bridge
- Thick-film resistors
- Gauge factor  $K_L \sim 12$

# Cantilever force cell – distances



## Geometry

- $L$  : for stress
- $d^+$  : positive signal (avg.)
- $d^-$  : positive signal (avg.)
- $d$  : signal (overall)
- $b$  : cantilever width
- $h$  : cantilever thickness

$$d = \frac{1}{2} (d^+ - d^-)$$

Nominal stress:

$$\sigma = \frac{6}{b \cdot h^2} \cdot L \cdot F$$

Effective sensor strain:

$$\varepsilon_r = \frac{6}{b \cdot h^2 \cdot E} \cdot d \cdot F$$

Response (signal / supply):

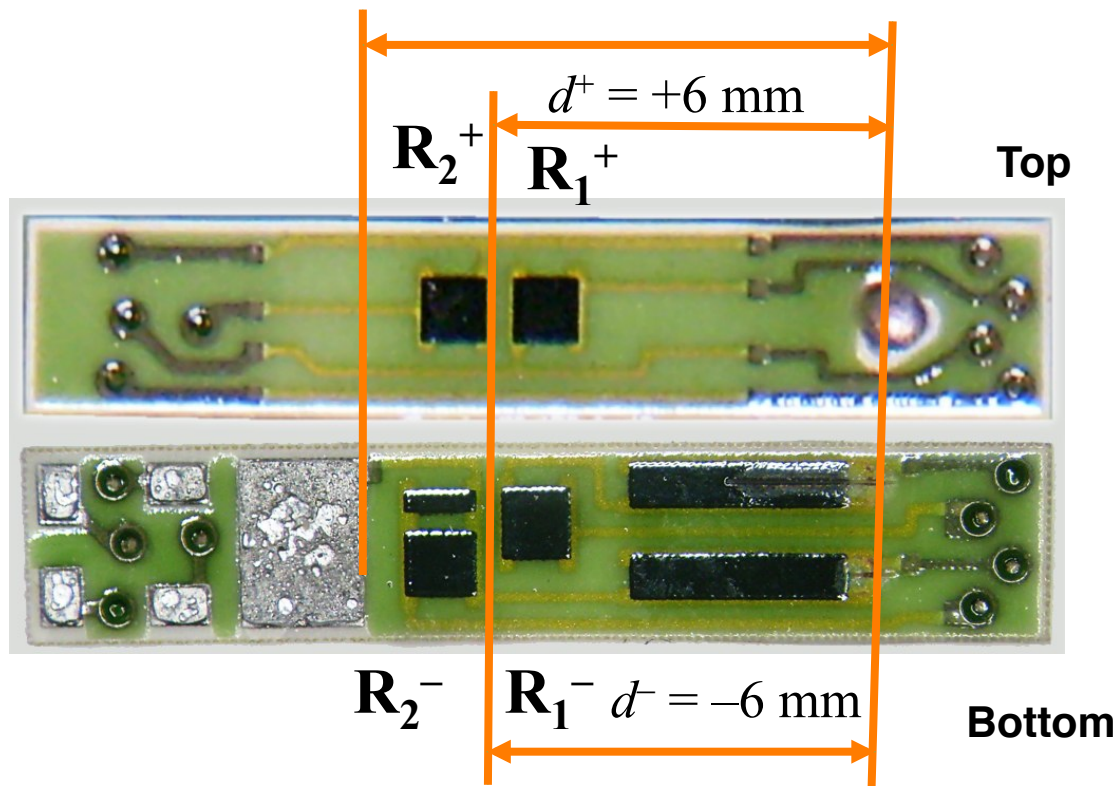
$$r = K_L \cdot \varepsilon_r$$

( $E$  = substrate elastic modulus;  $K_L$  = piezoresistive longitudinal gauge factor)

# Classical cantilever

$$d / L = 75\%$$

$$L = 8 \text{ mm}$$



## Pros

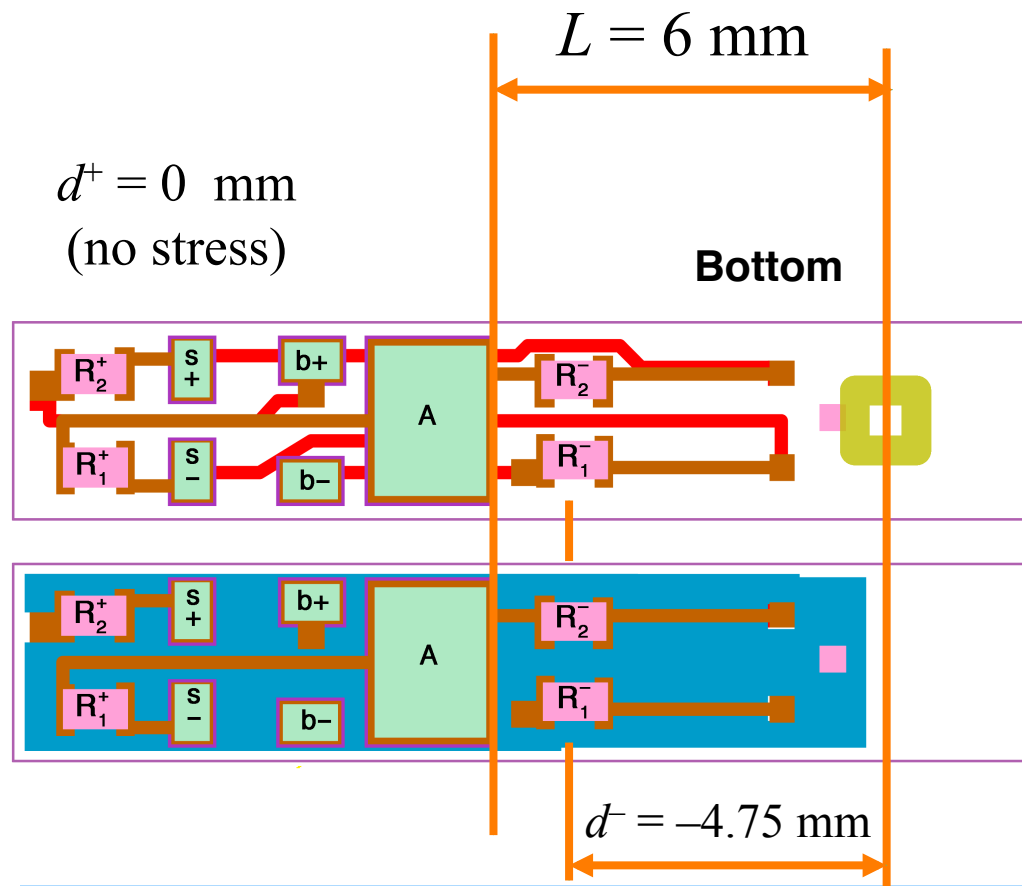
- Full active bridge
- Little thermal drift

## Cons

- Double-side, complex fabrication
- More difficult resistor matching (separate prints)
- Layers on top side
- Sensitive to horizontal forces

# Single-side cantilever (type 1)

$$d / L = 40\%$$



## Pros

- Single-side, simple
- Good resistor matching (single print)
- Blank top side
- Little thermal drift

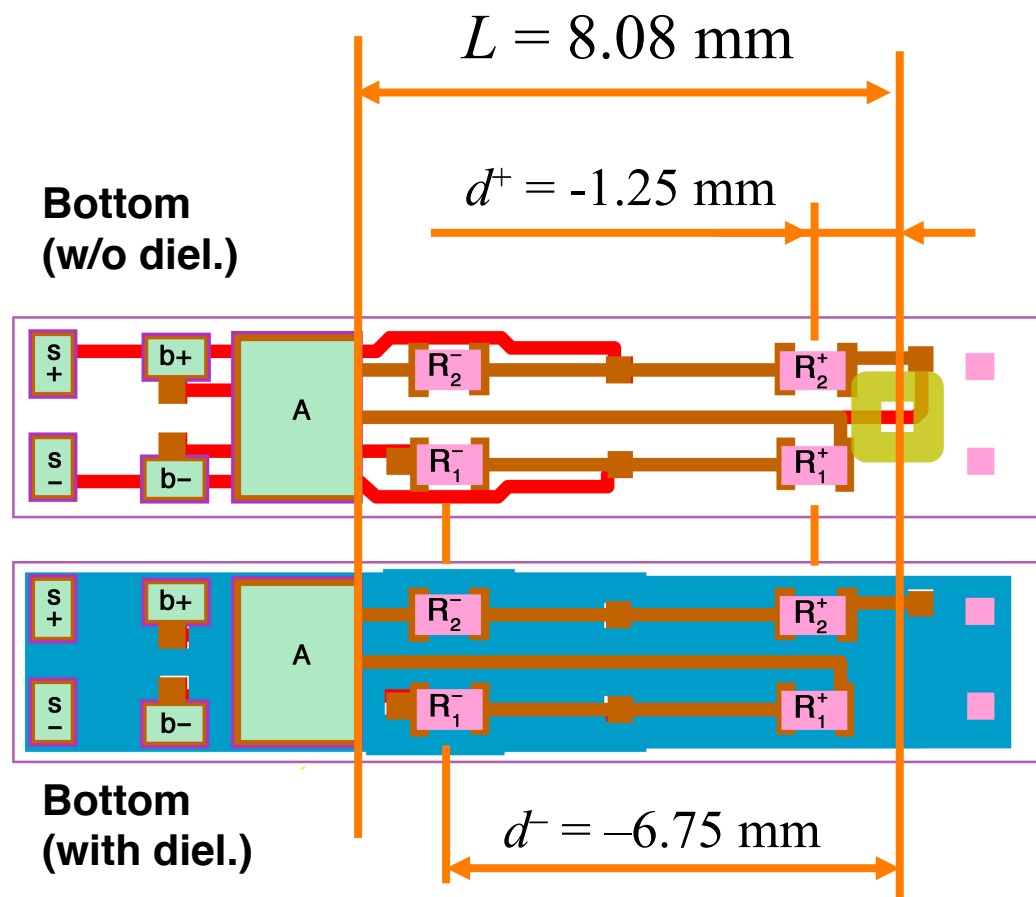
## Cons

- Half bridge, less sensitive
- Sensitive to horizontal forces



# Single-side cantilever (types 2/3)

$$d / L = 34\%$$



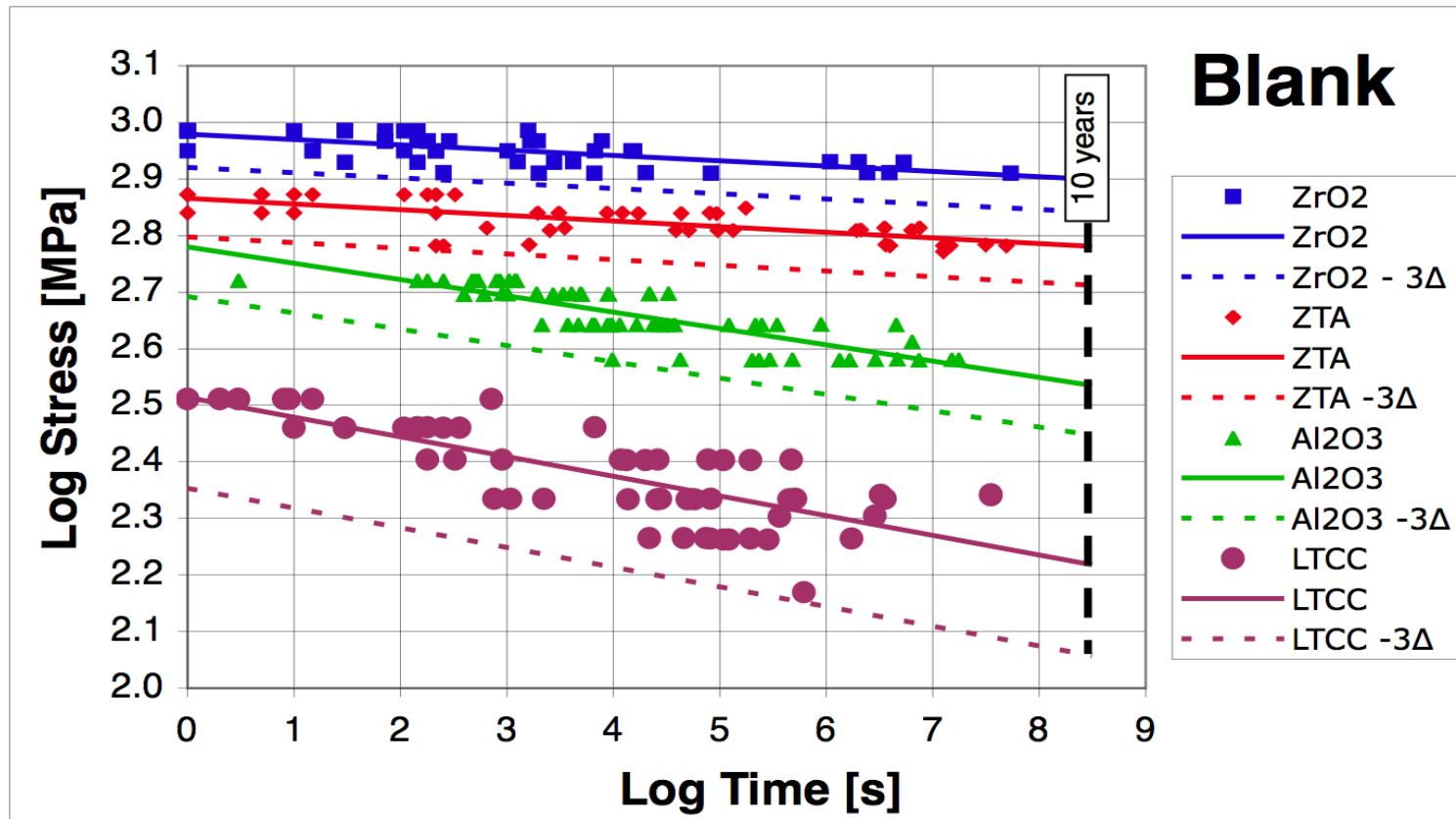
## Pros

- Single-side, simple
- Good resistor matching (single print)
- Blank top side
- Horizontal force compensation

## Cons

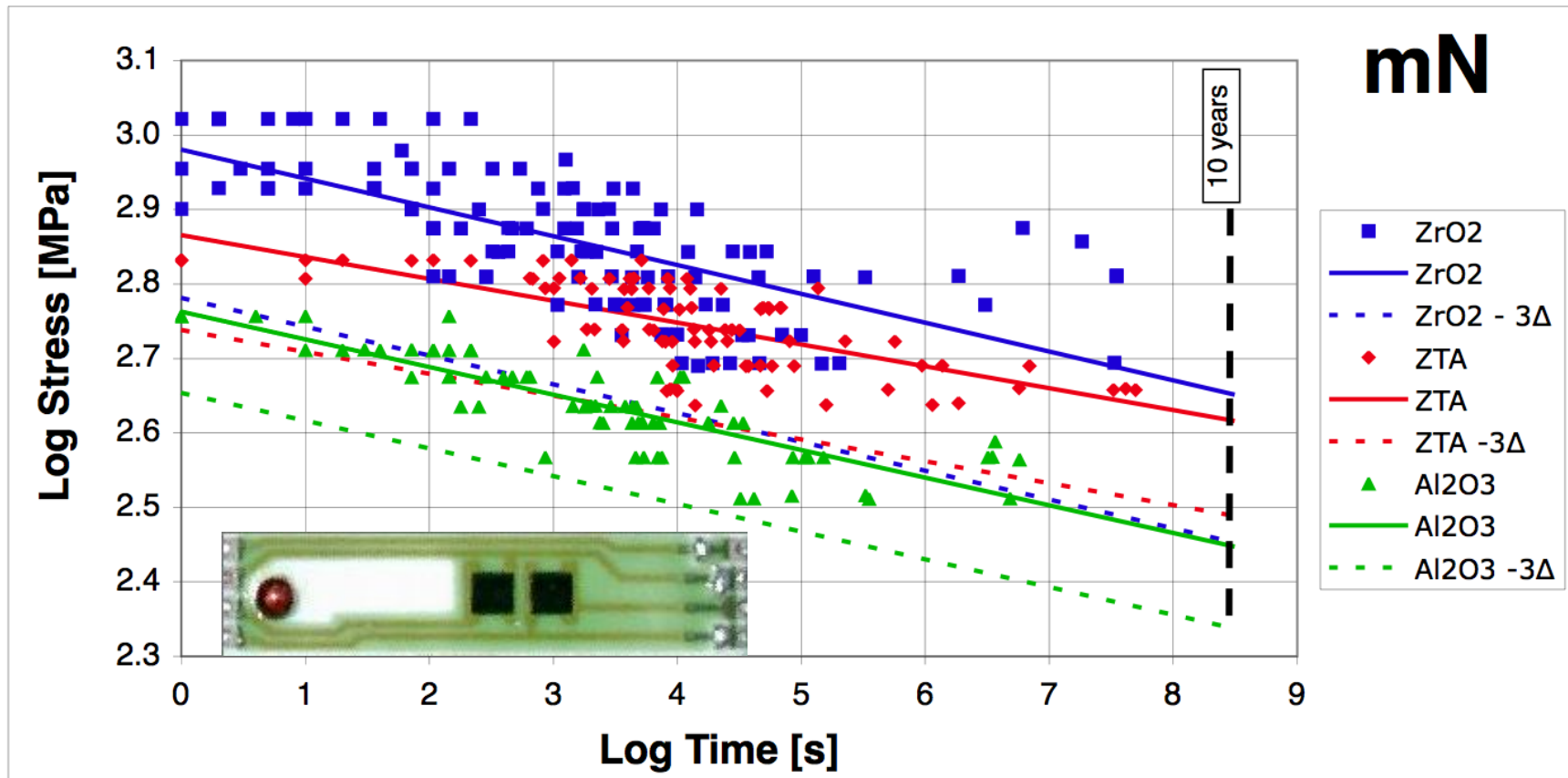
- Half bridge, sensitivity further reduced by "retrograde" resistors
- Buried conductors?

# Substrates (blank) – static fatigue



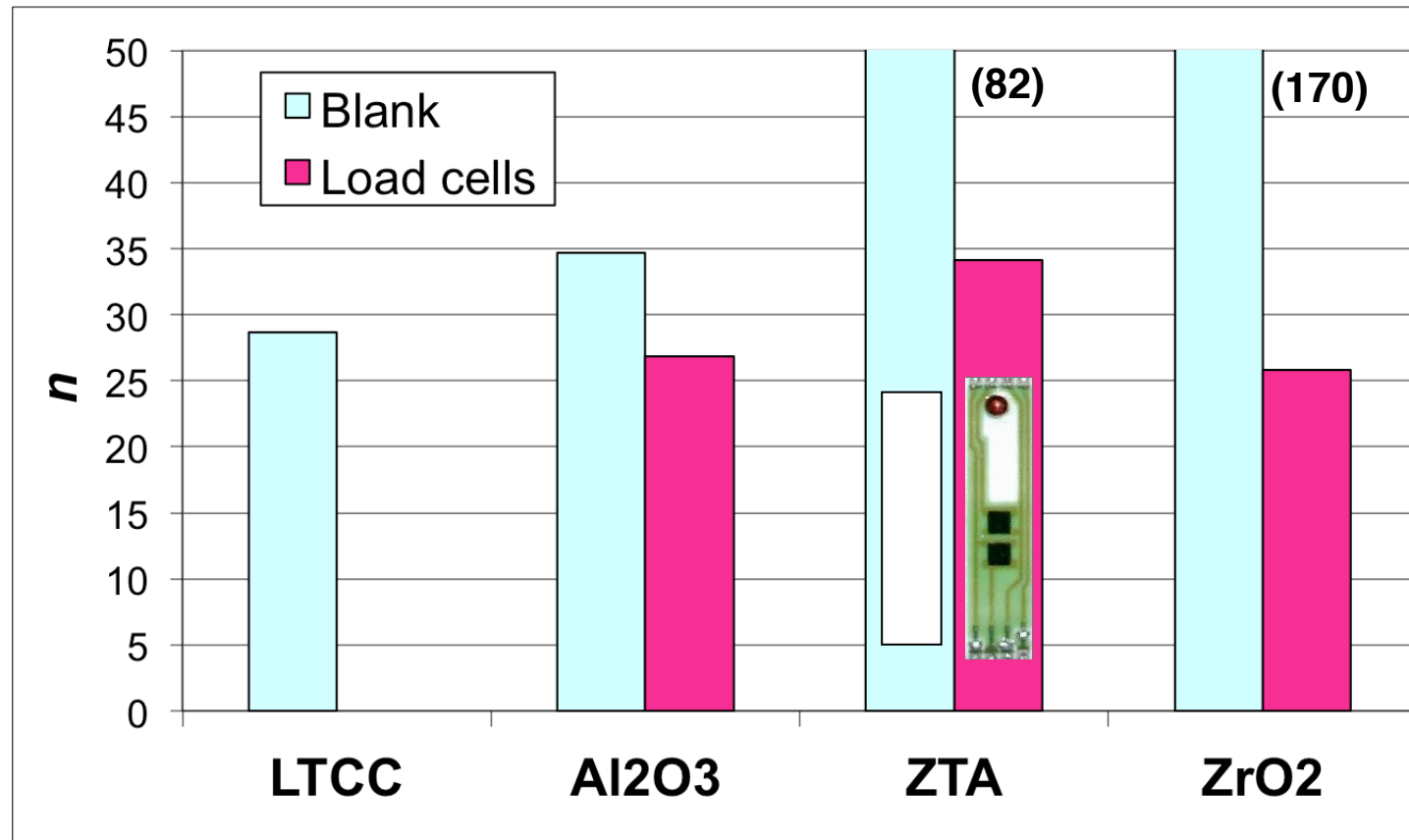
- Very good performance for ZrO<sub>2</sub>:Y (YSZ) & ZTA
- Glassy (Al<sub>2</sub>O<sub>3</sub> 96% & LTCC) : poorer

# Substrates (load cell) – static fatigue



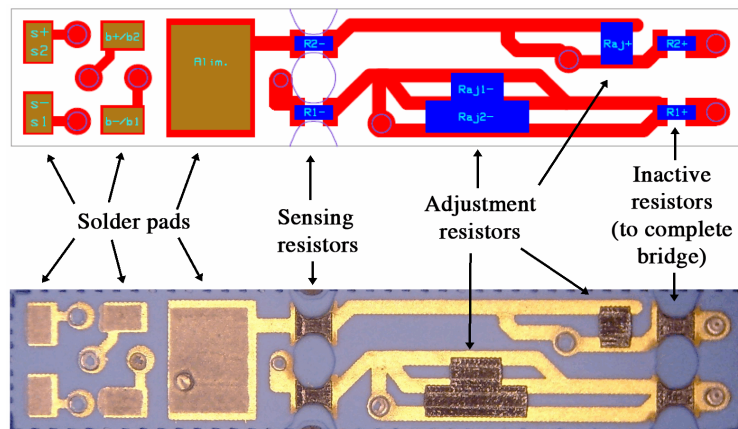
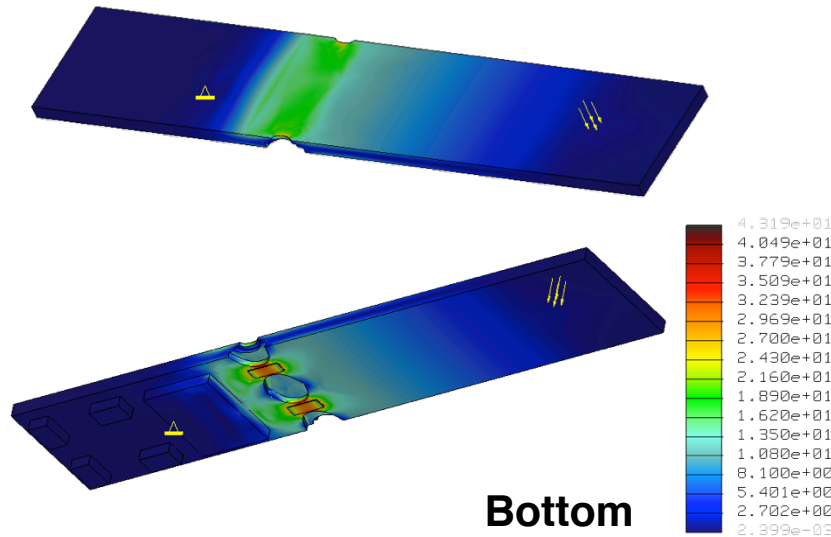
- Strong degradation of high-strength substrates (ZrO<sub>2</sub> & ZTA)
- ZrO<sub>2</sub> & ZTA better with single-side cantilevers (blank top side)

# Substrates (load cell) – static fatigue



- Strong degradation of high-strength substrates (ZrO<sub>2</sub> & ZTA)
- ZrO<sub>2</sub> & ZTA better with single-side cantilevers (blank top side)

# LTCC structured cantilever



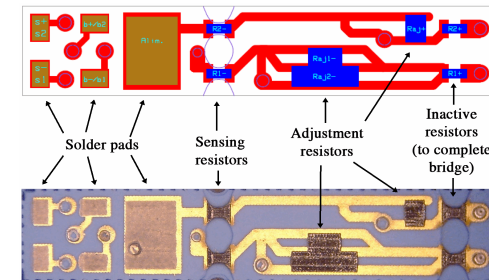
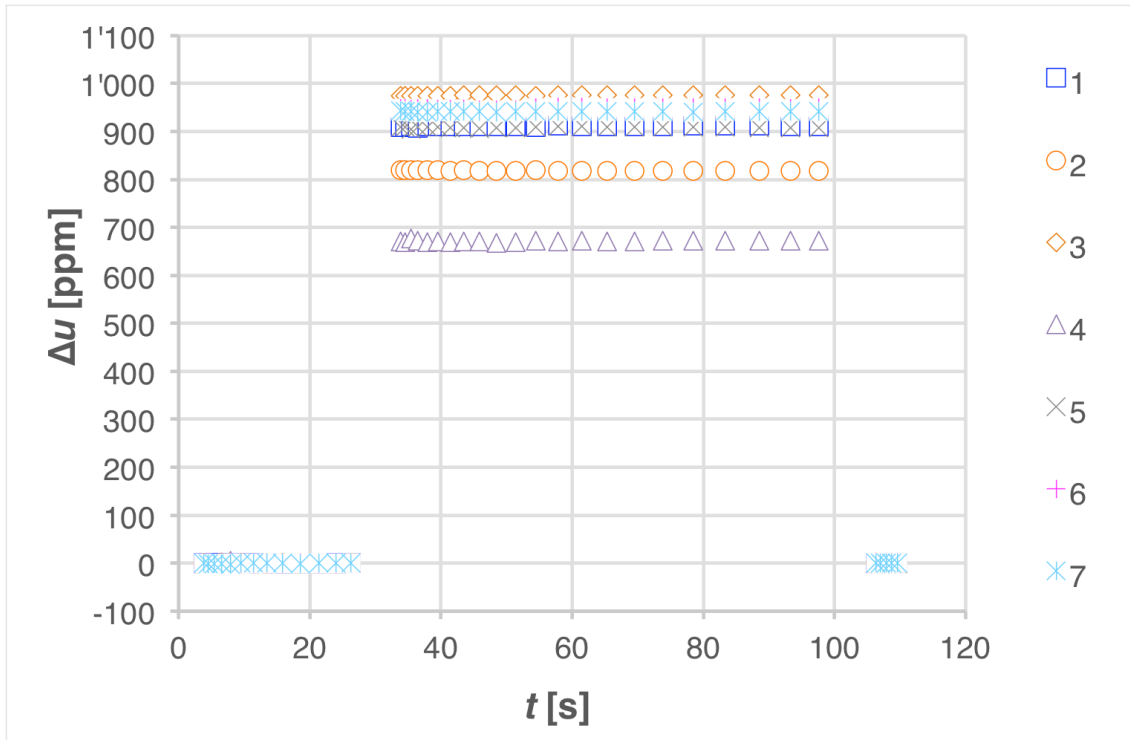
## Pros

- Single-side
- Good resistor matching
- **Higher signal by structuration**
  - Concentration of compression
  - In practice ~2x
- Horizontal force compensation

## Cons

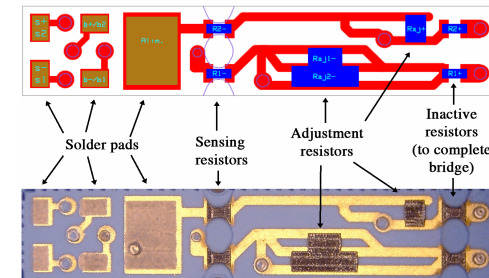
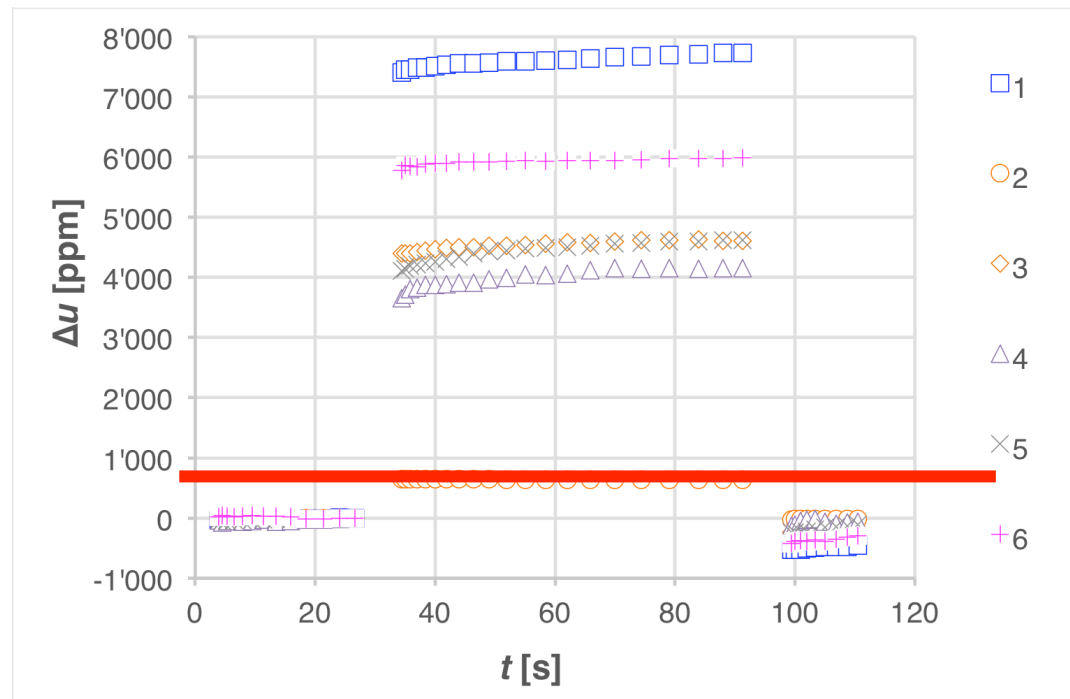
- LTCC process critical for thin, sensitive cantilevers (shrinkage matching, warpage)
- Resistor compatibility
- **Drift???**

# LTCC cantilever – drift ?



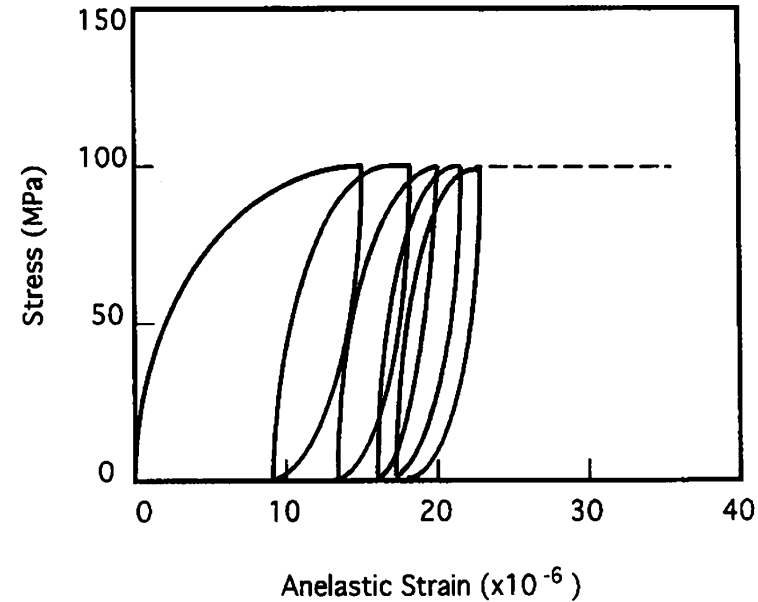
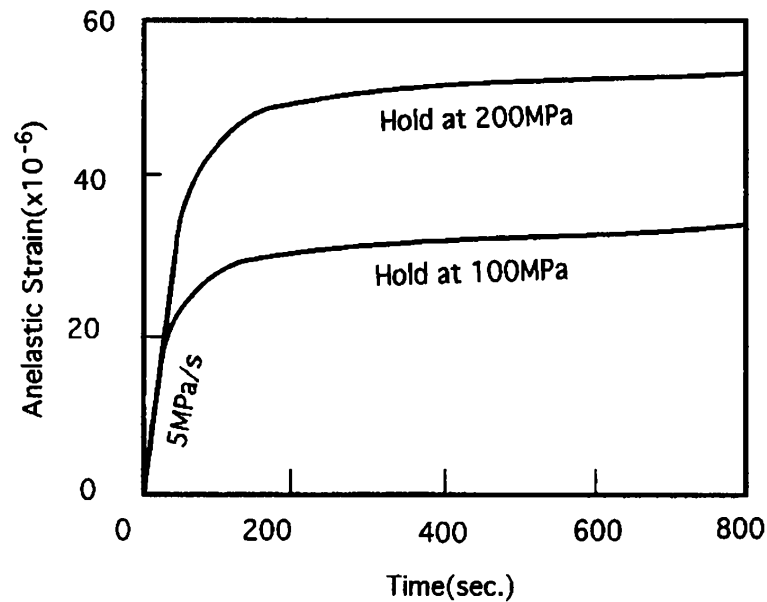
- Moderate, consistent signal
- No apparent drift

# LTCC cantilever – drift ?



- Abnormally high signal
- Strong variations between samples
- Significant drift

# YSZ cantilevers – drift?



Pan & Horibe, Acta Mater. 1997

## Anelasticity in YSZ

- Ferroelasticity
- Problematic for elastic substrate...



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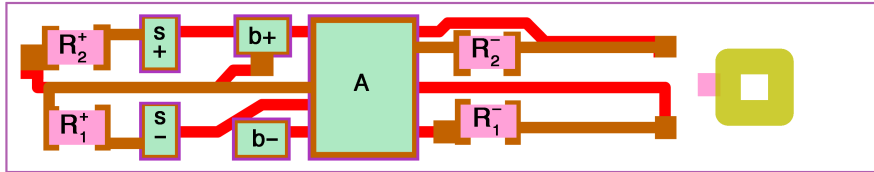
# Substrates

Code	Substrate material	Thickness [ $\mu\text{m}$ ]
A	3YSZ (Kerafol)	45
B	3YSZ (Kerafol)	90
C	Al <sub>2</sub> O <sub>3</sub> 96% (Kyocera A-476)	400
D	Al <sub>2</sub> O <sub>3</sub> 96% (CeramTec Rubalit 708S)	150
E	ZTA (CeramTec Rubalit HSS 2-14-02-004)	250
F	ZTA (CeramTec Rubalit HSS4-38/3 S2)	320
G	LTCC (Heraeus CT700)	470 / 710
H	LTCC (Heraeus Heralock HL2000)	180 / 270
I	LTCC (DuPont 951)	270 / 410

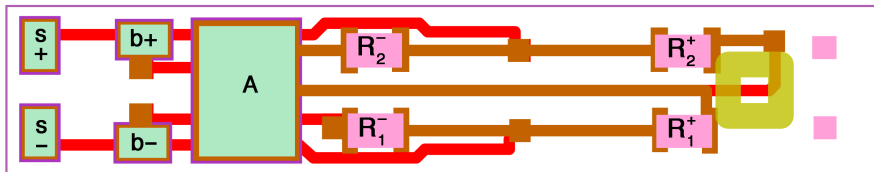
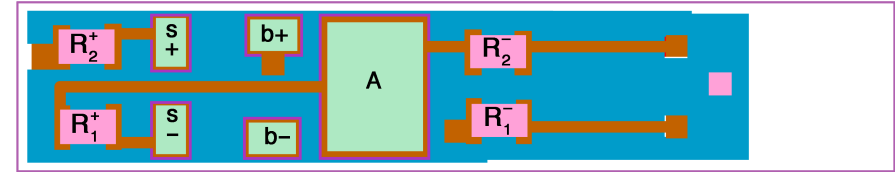
## Tested substrates

- All pre-fired
- Not structured, same layout

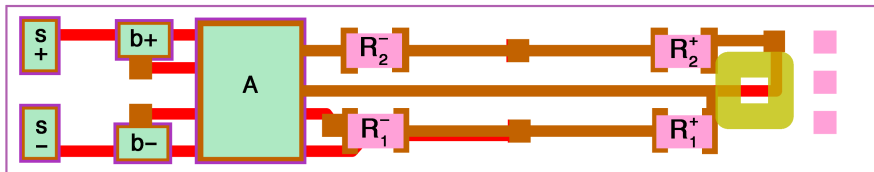
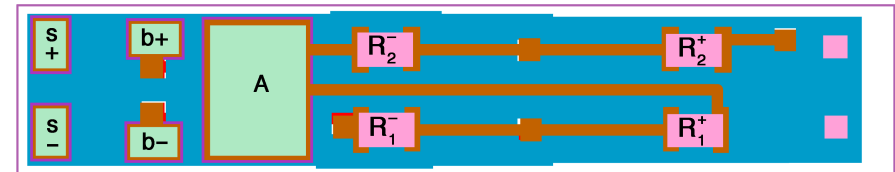
# Layouts



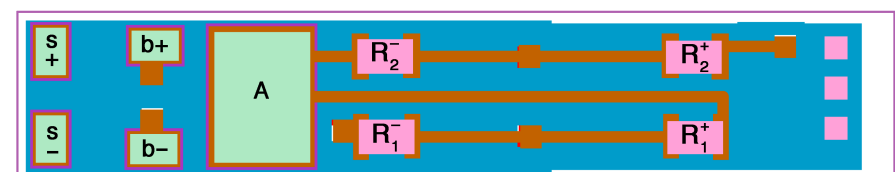
1



2



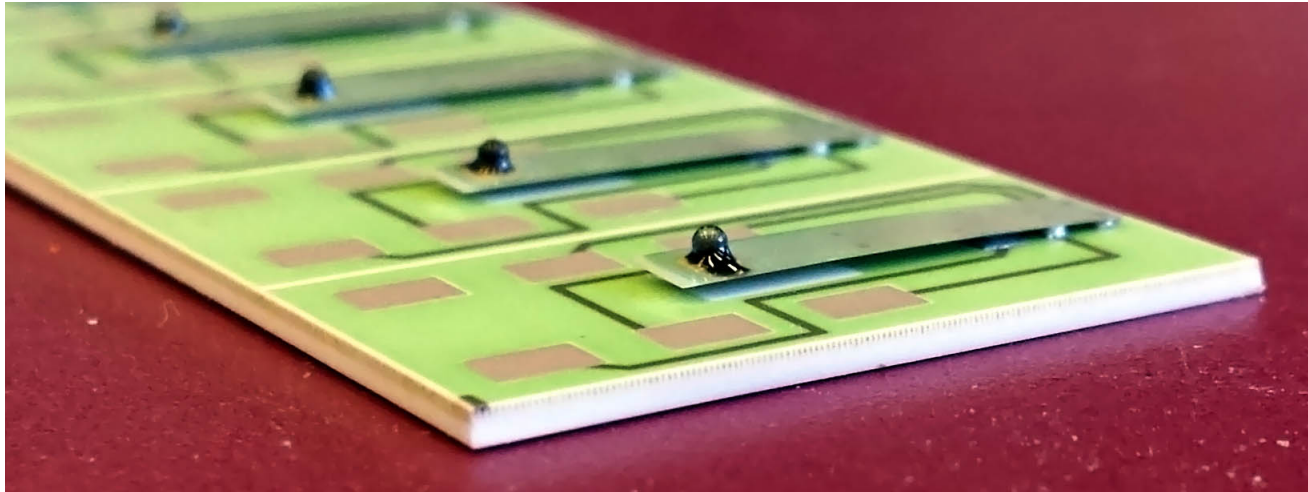
3



## Tested layouts

- 1) Short cantilever, half-bridge
- 2) Long cantilever (no tracks under resistors)
- 3) Long cantilever (tracks under resistors)

# Fabrication



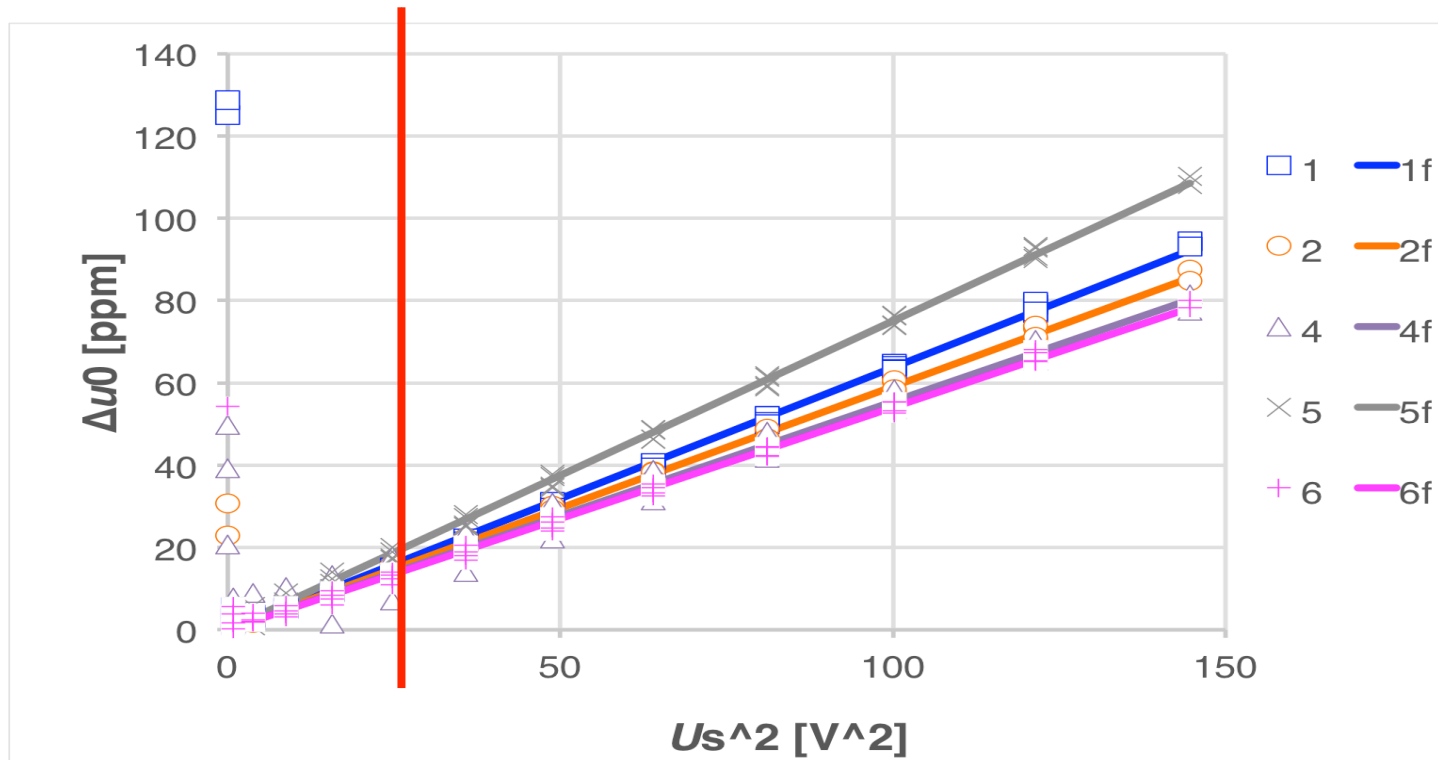
- Resistors (DP 2041) on dielectric:
  - 3YSZ : ESL 4931 (for steel -> CTE ~ YSZ)
  - Others : ESL 4913 + 4917 (low CTE)
- 3YSZ : 45  $\mu\text{m}$  critical, 90  $\mu\text{m}$  OK
- $\text{Al}_2\text{O}_3$  / ZTA : OK down to 150  $\mu\text{m}$  (ZTA recommended)
- LTCC : flatness critical (DP951  $\gtrsim$  HL2000  $>$  CT700)

# Outline

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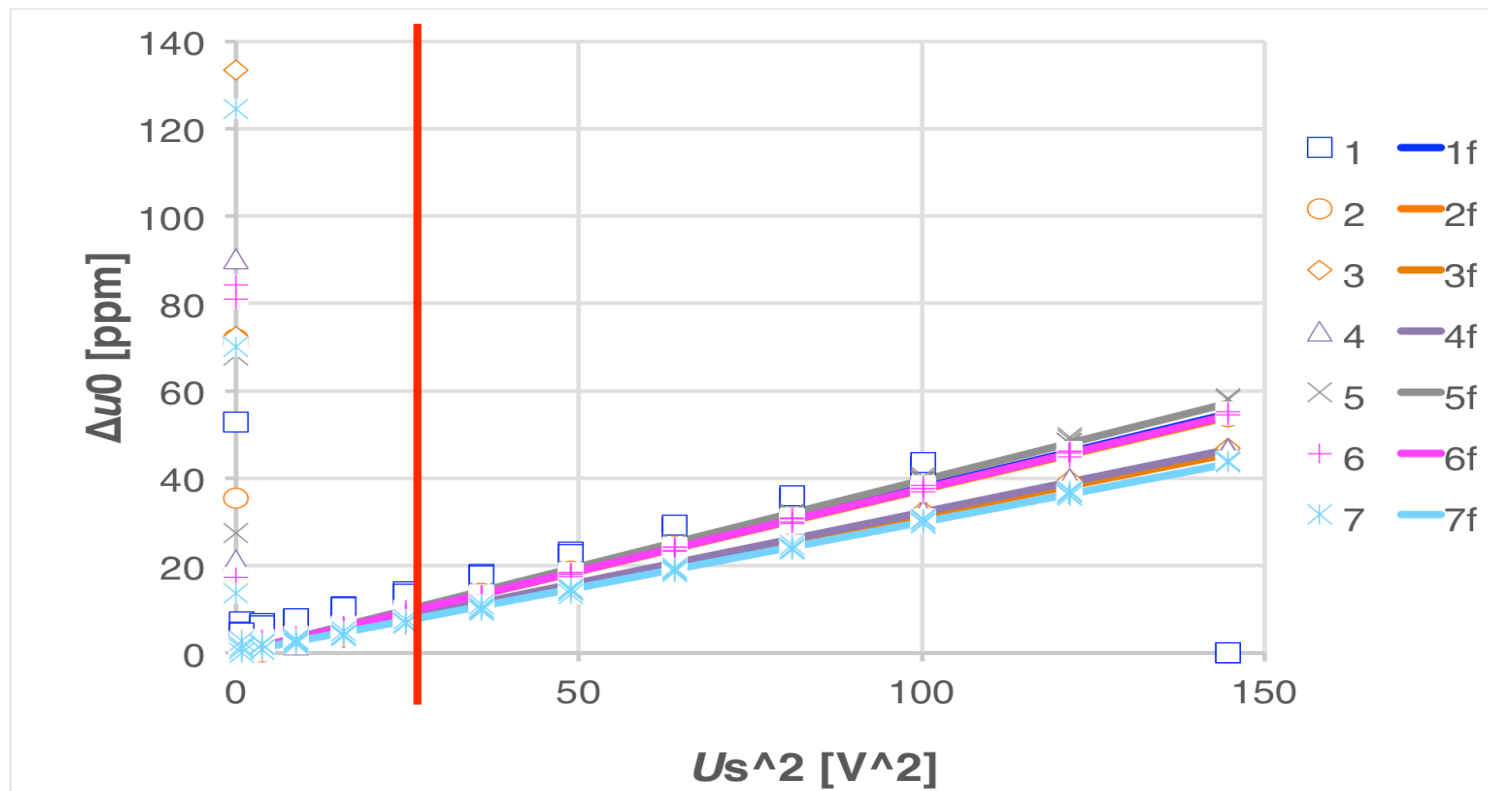
1. Introduction
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# A – 45 $\mu\text{m}$ 3YSZ – layout 3



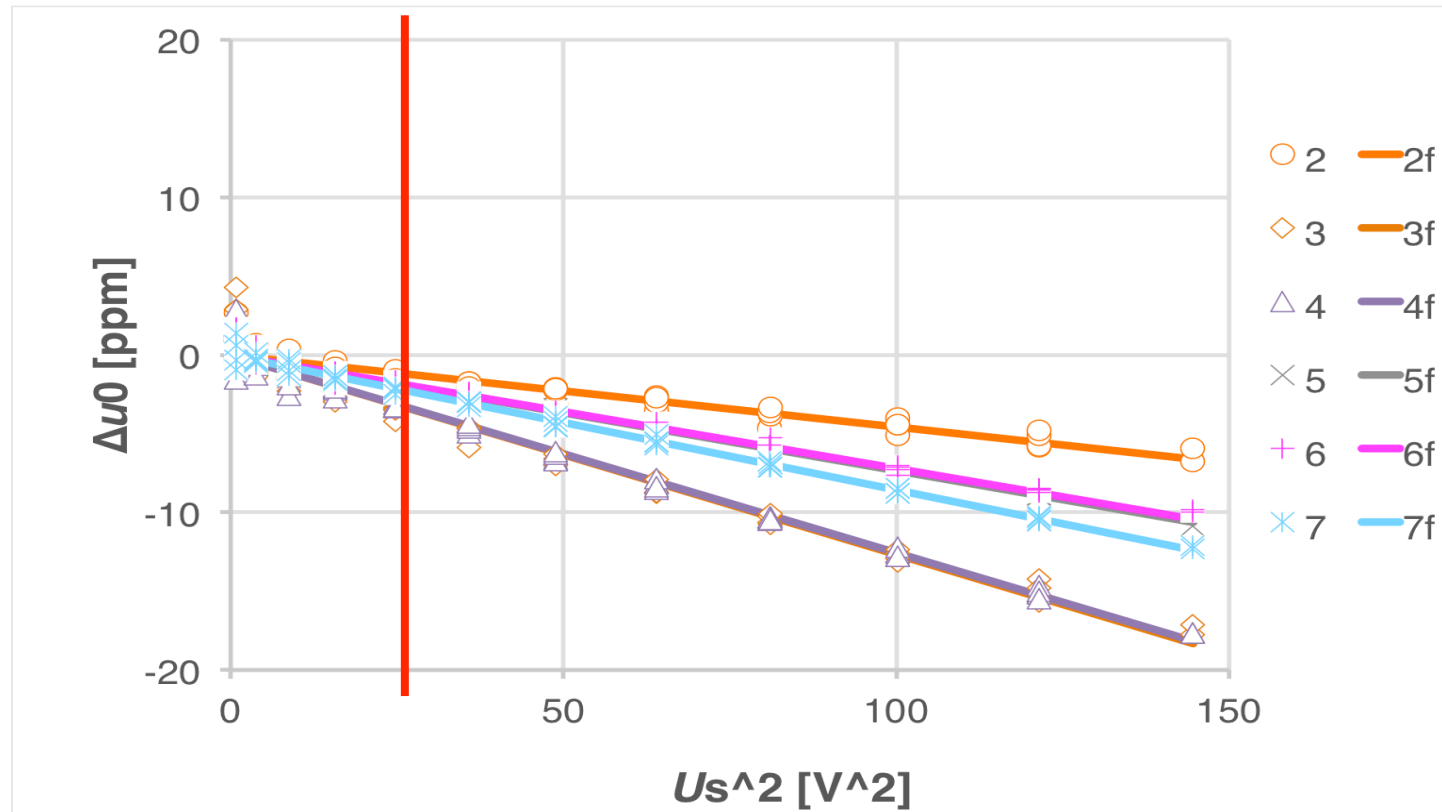
- Very low heat conductance (45  $\mu\text{m}$  thick,  $k \sim 2\text{-}3$  W/m/K)
- Thermal drift max  $\sim 1\%$  (for 2'000 ppm F.S.)

# B – 90 $\mu\text{m}$ 3YSZ – layout 2



- Same material, 2x thickness
- 1/2 thermal drift

# D – 150 $\mu\text{m}$ alumina – layout 2



- Very low thermal drift even for thinnest  $\text{Al}_2\text{O}_3$

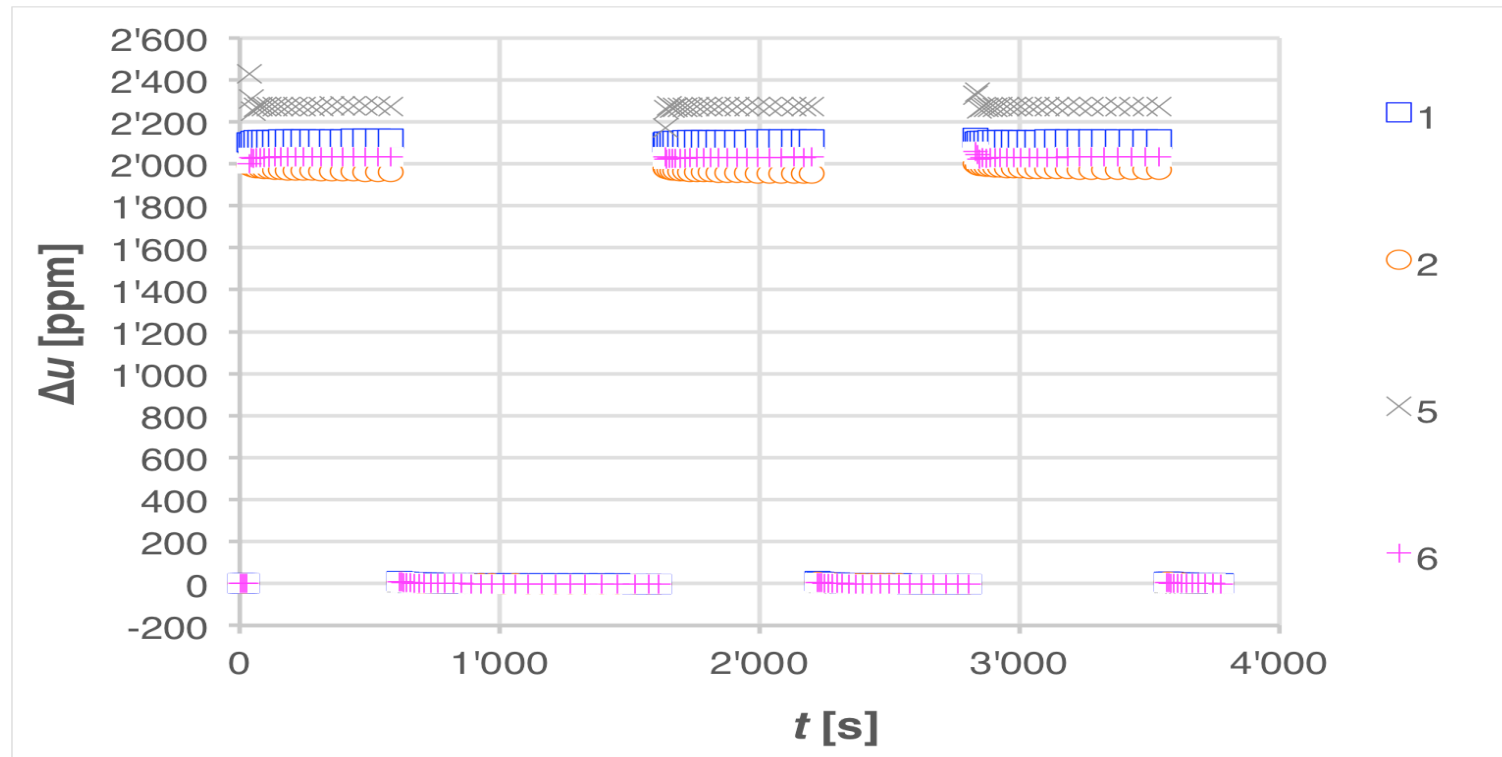


# Outline

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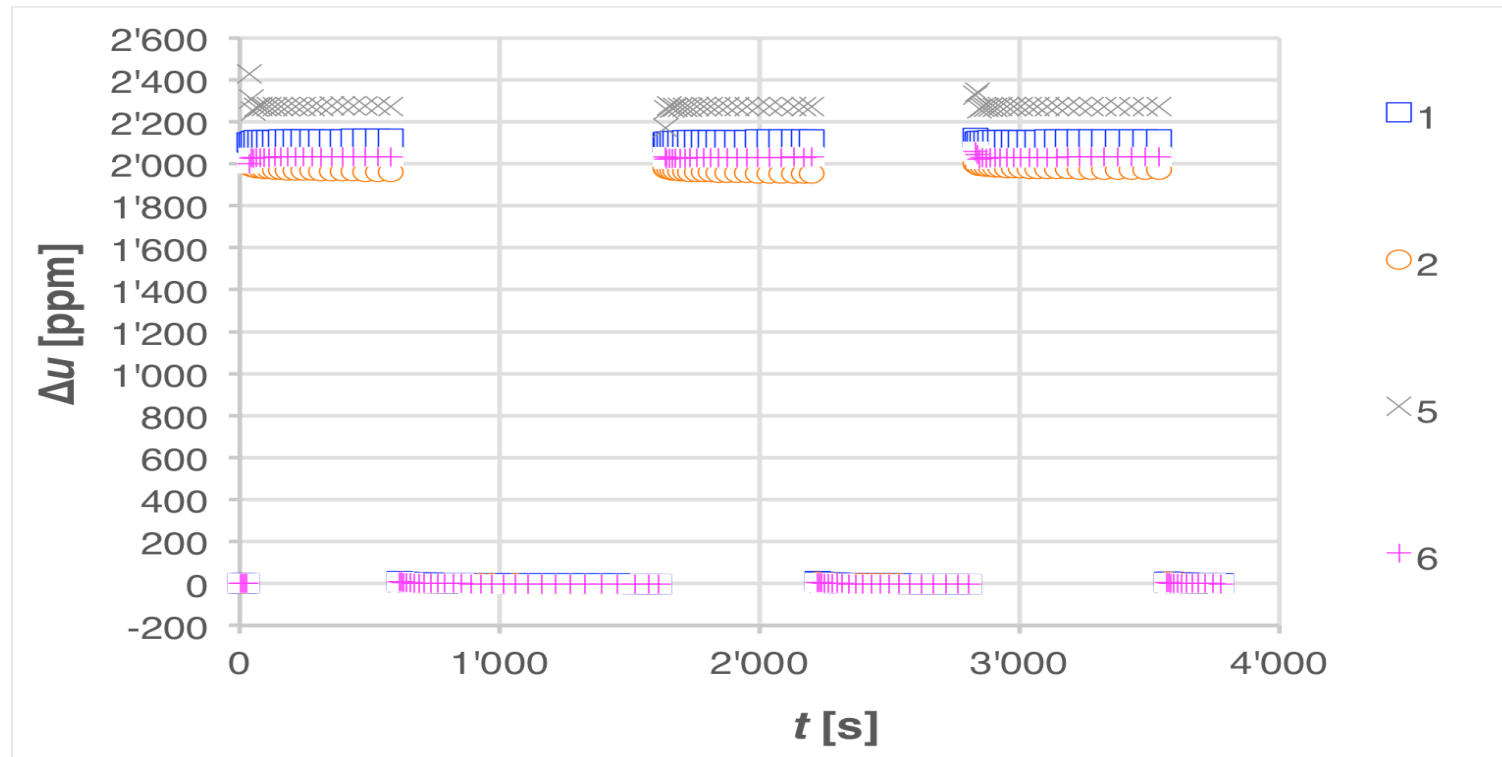
1. Introduction
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# A – 45 $\mu\text{m}$ 3YSZ – layout 3



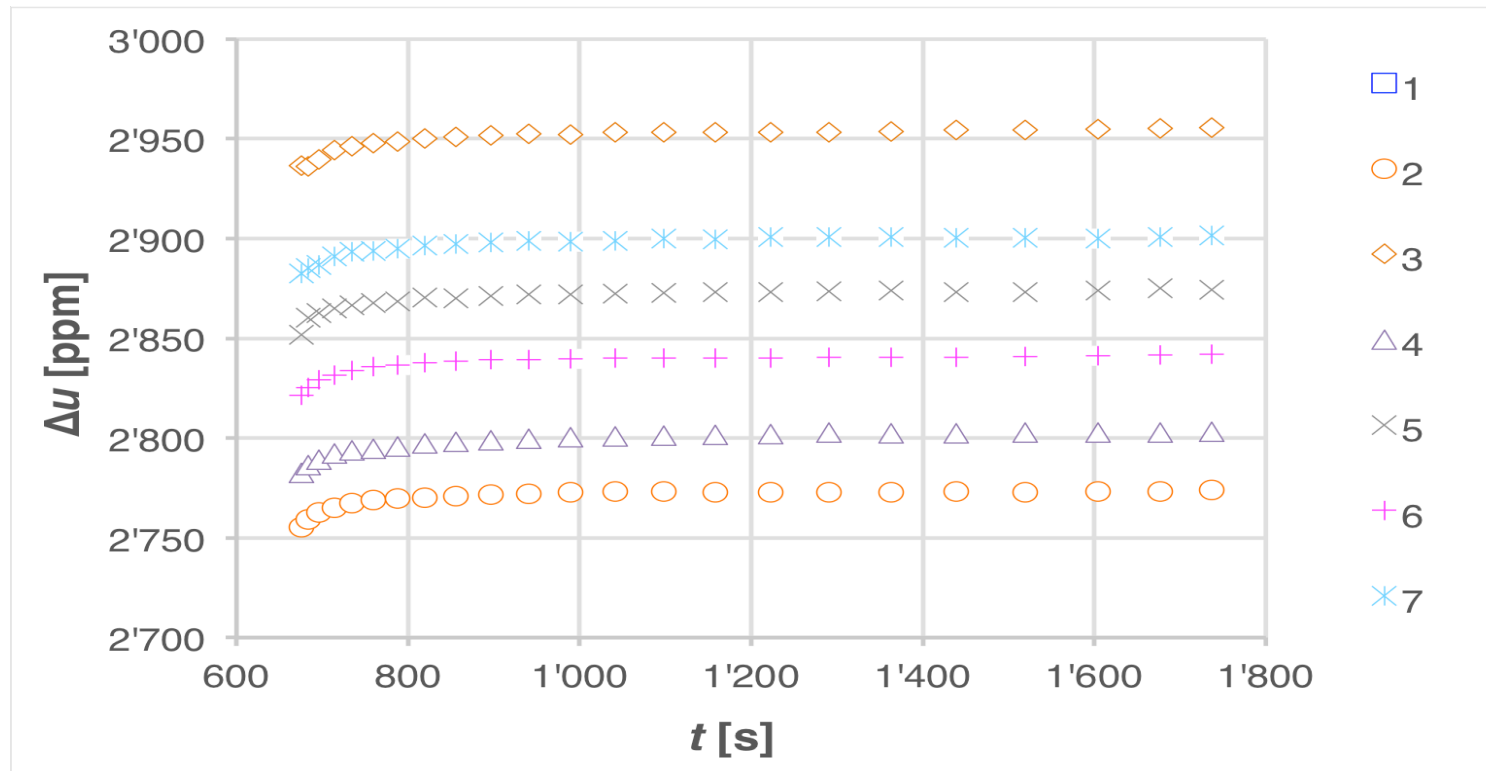
- High signal level, consistent
- No visible drift ( $<\pm 5$  ppm)
- Linear signal,  $\sim 43$  ppm/mN

## B – 90 $\mu\text{m}$ 3YSZ – layout 2



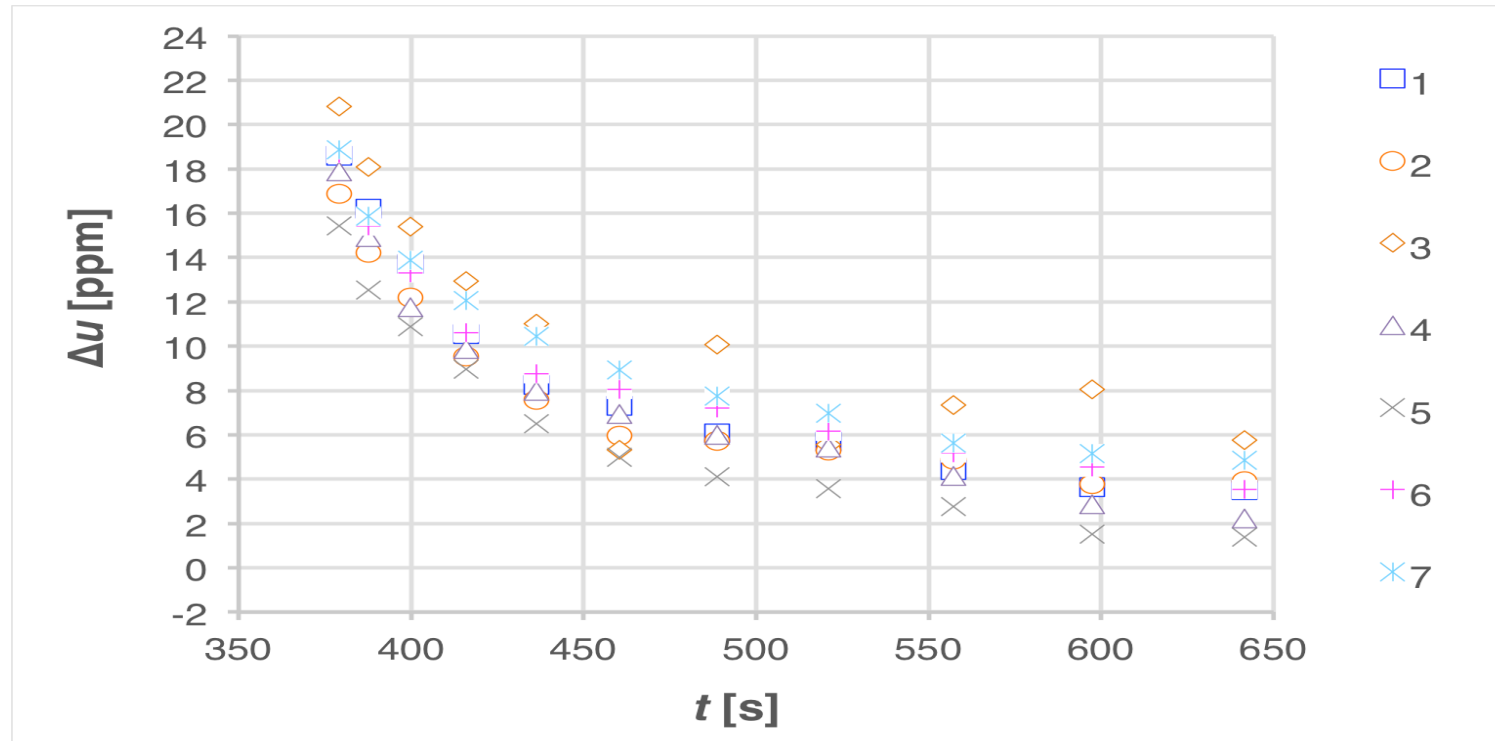
- High signal level, quite consistent
- Linear signal,  $\sim 20$  ppm/mN
- Slight drift?

# B – 90 $\mu\text{m}$ 3YSZ – layout 2 (loading)



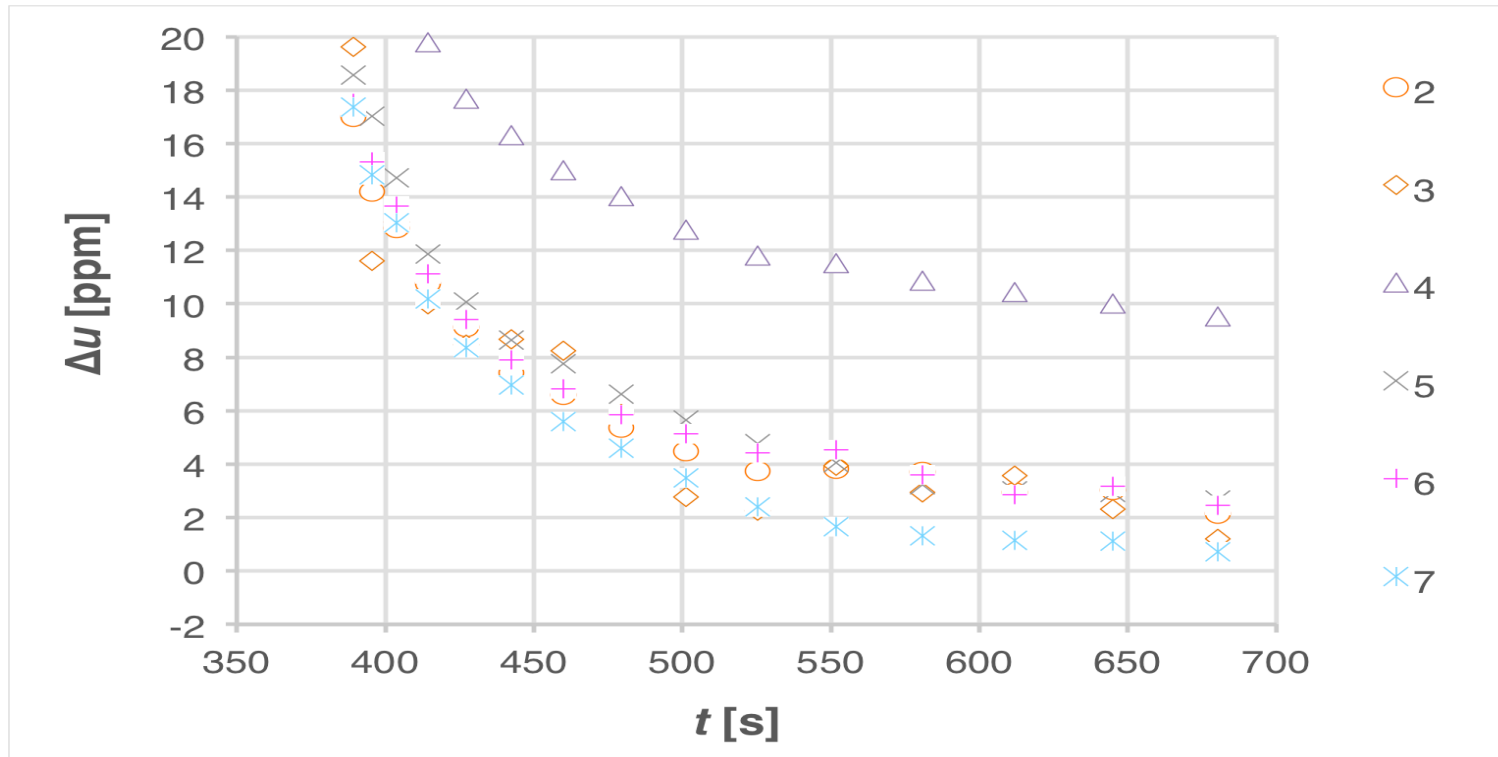
- High signal level, quite consistent
- Linear signal,  $\sim 20$  ppm/mN
- Slight drift?

## B – 90 $\mu\text{m}$ 3YSZ – layout 2 (unloading)



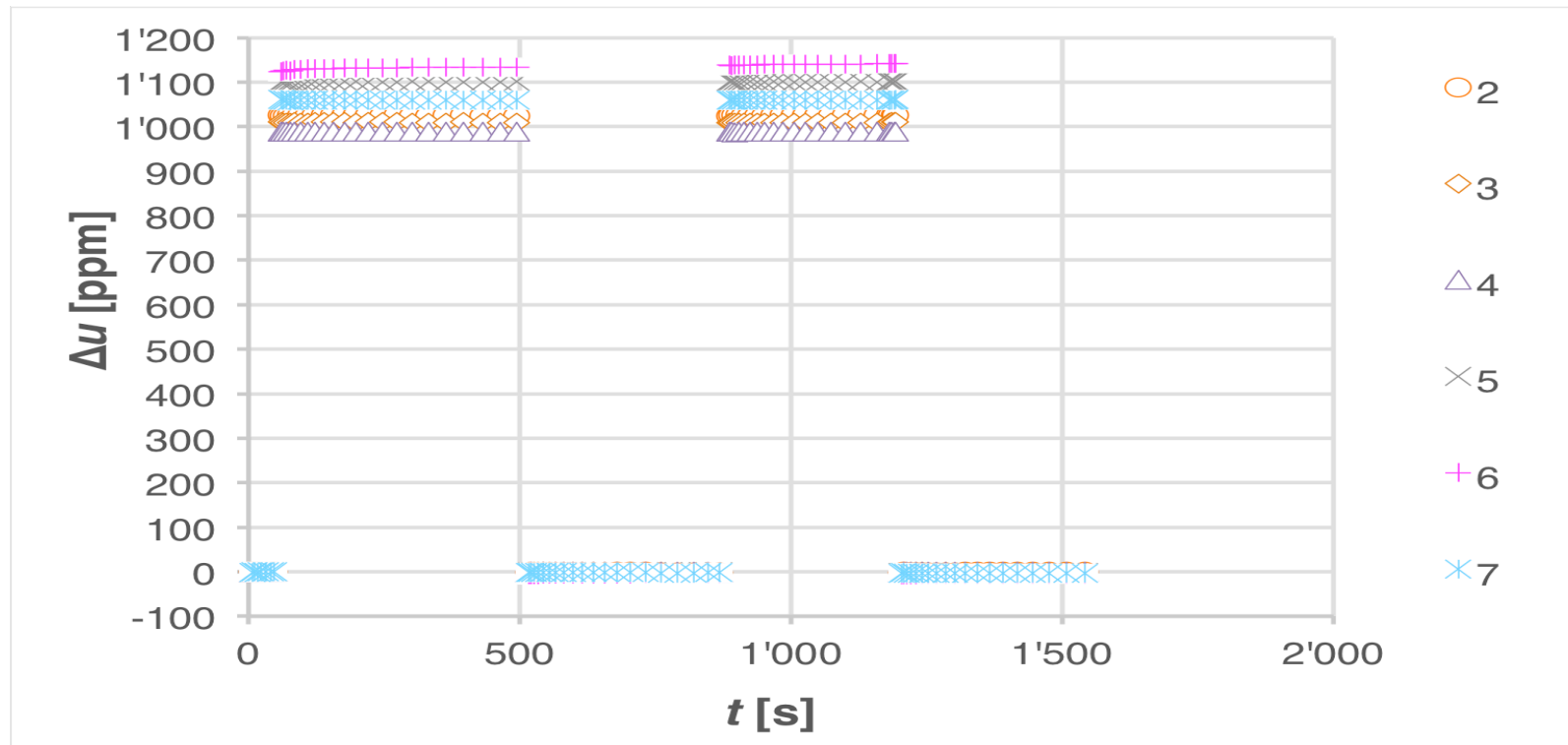
- High signal level, quite consistent
- Linear signal,  $\sim 20$  ppm/mN
- Slight drift?

# B – 90 $\mu\text{m}$ 3YSZ – layout 3 (unloading)



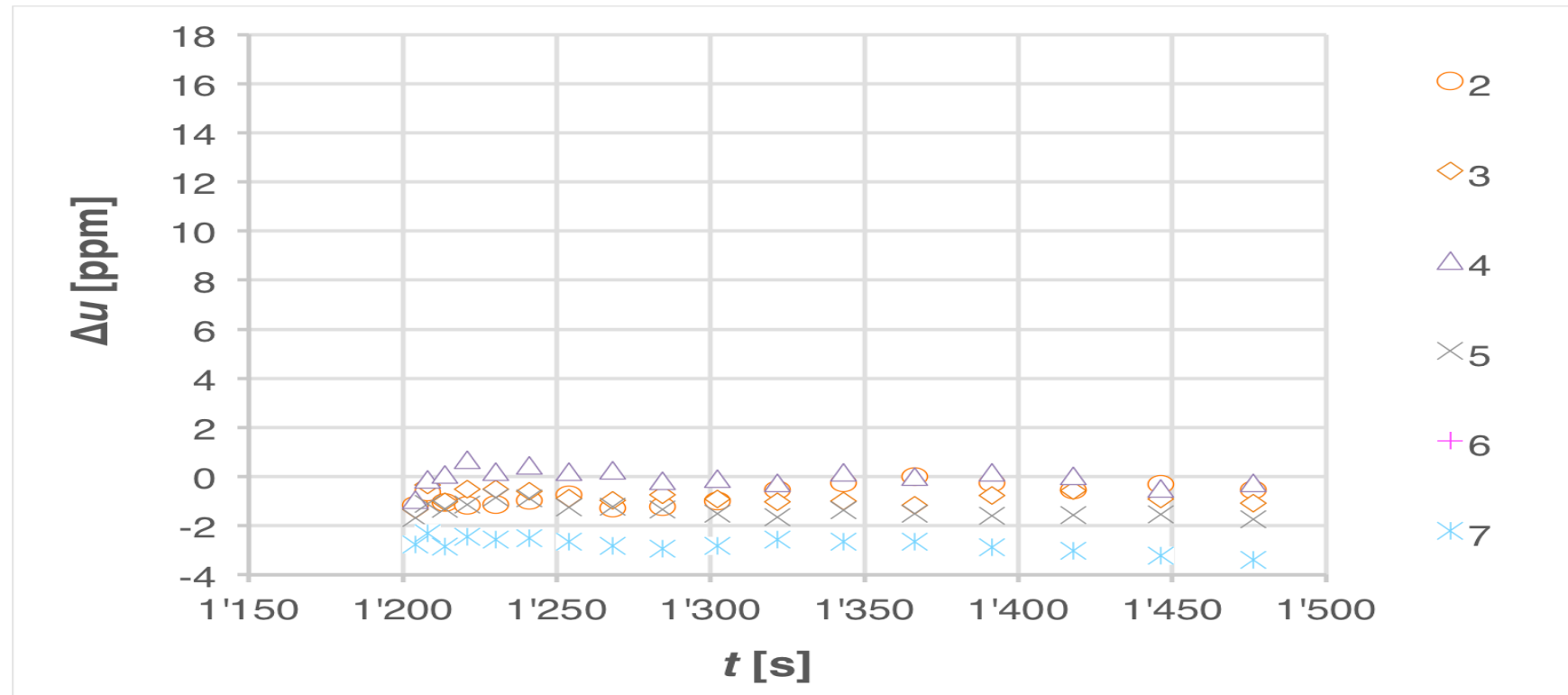
- Apparent drift similar for both layouts

## D – 150 $\mu\text{m}$ $\text{Al}_2\text{O}_3$ – layout 2



- Expected magnitude vs 90  $\mu\text{m}$  YSZ (B) & 400  $\mu\text{m}$   $\text{Al}_2\text{O}_3$  (C)
- Very clean signal

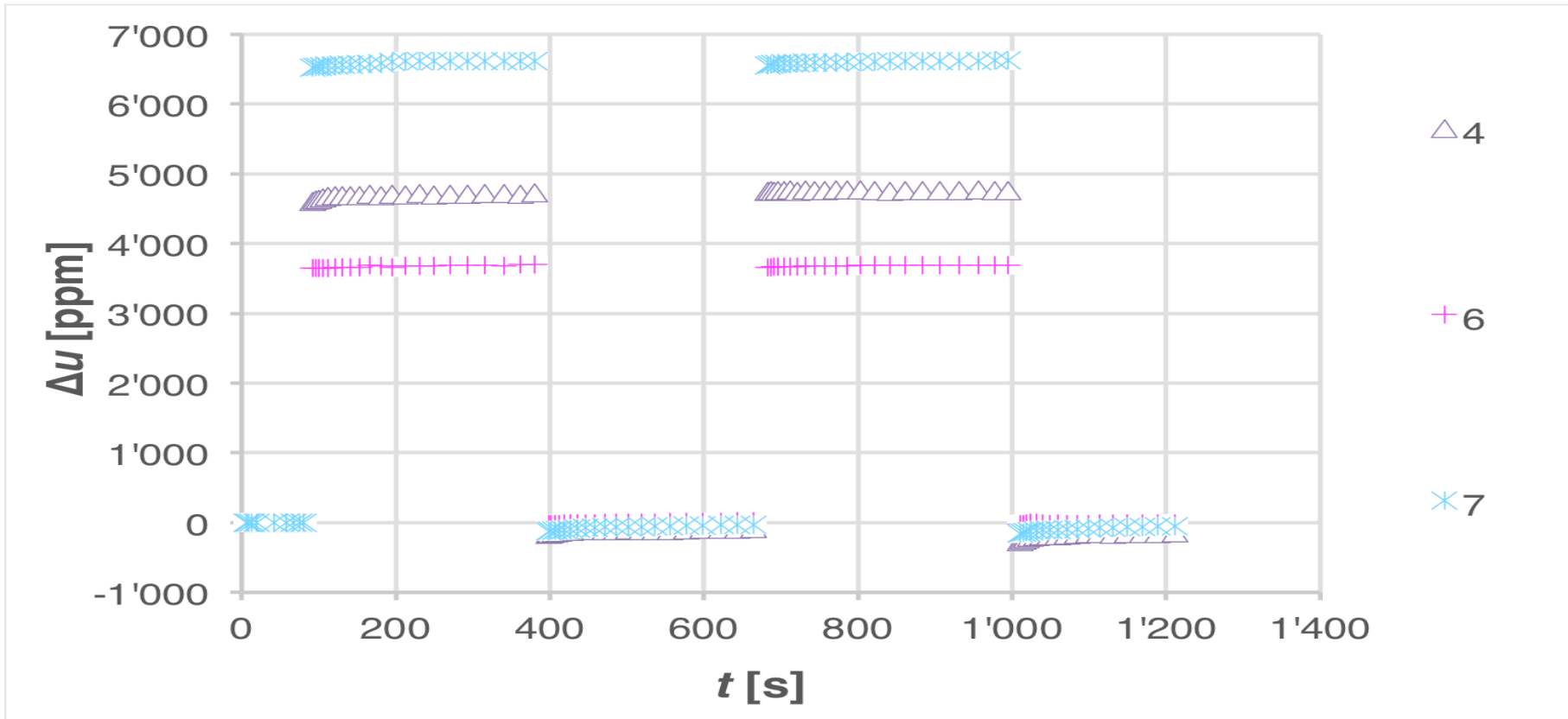
## D – 150 $\mu\text{m}$ $\text{Al}_2\text{O}_3$ – layout 2 (unloading)



- Expected magnitude vs 90  $\mu\text{m}$  YSZ (B) & 400  $\mu\text{m}$   $\text{Al}_2\text{O}_3$  (C)
- Very clean signal

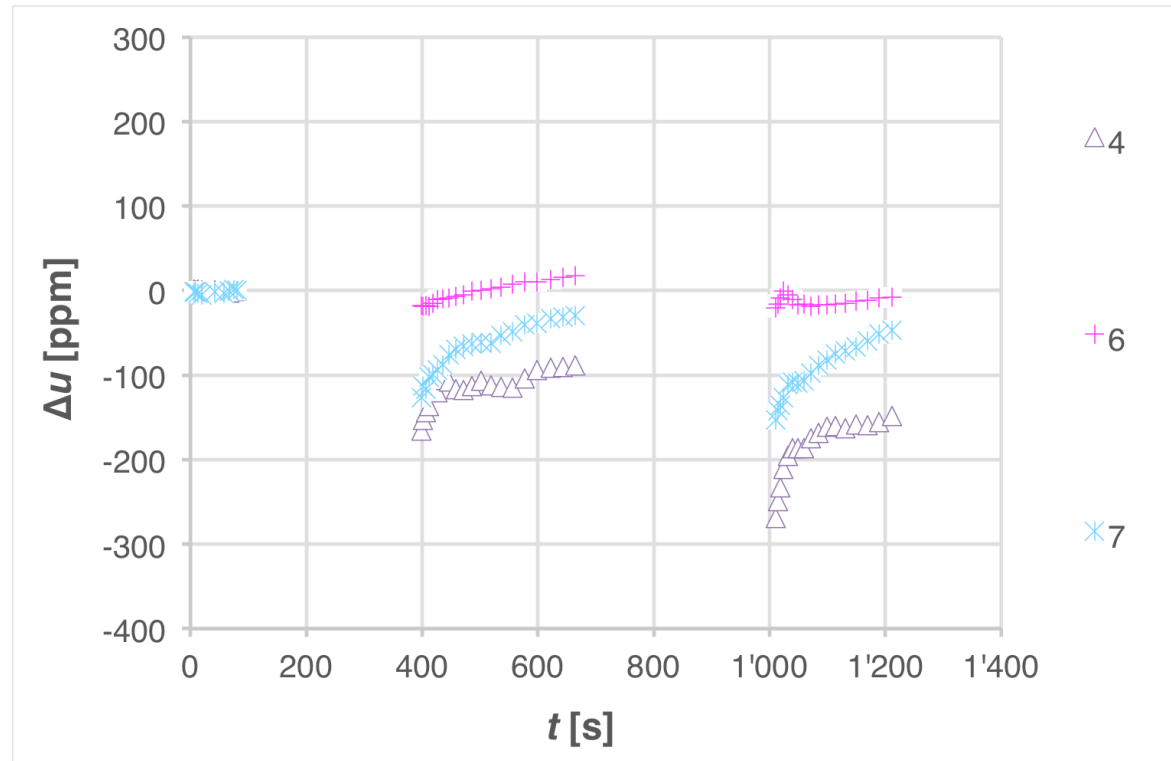


# H2 – 180 $\mu\text{m}$ LTCC HL2000 – layout 3



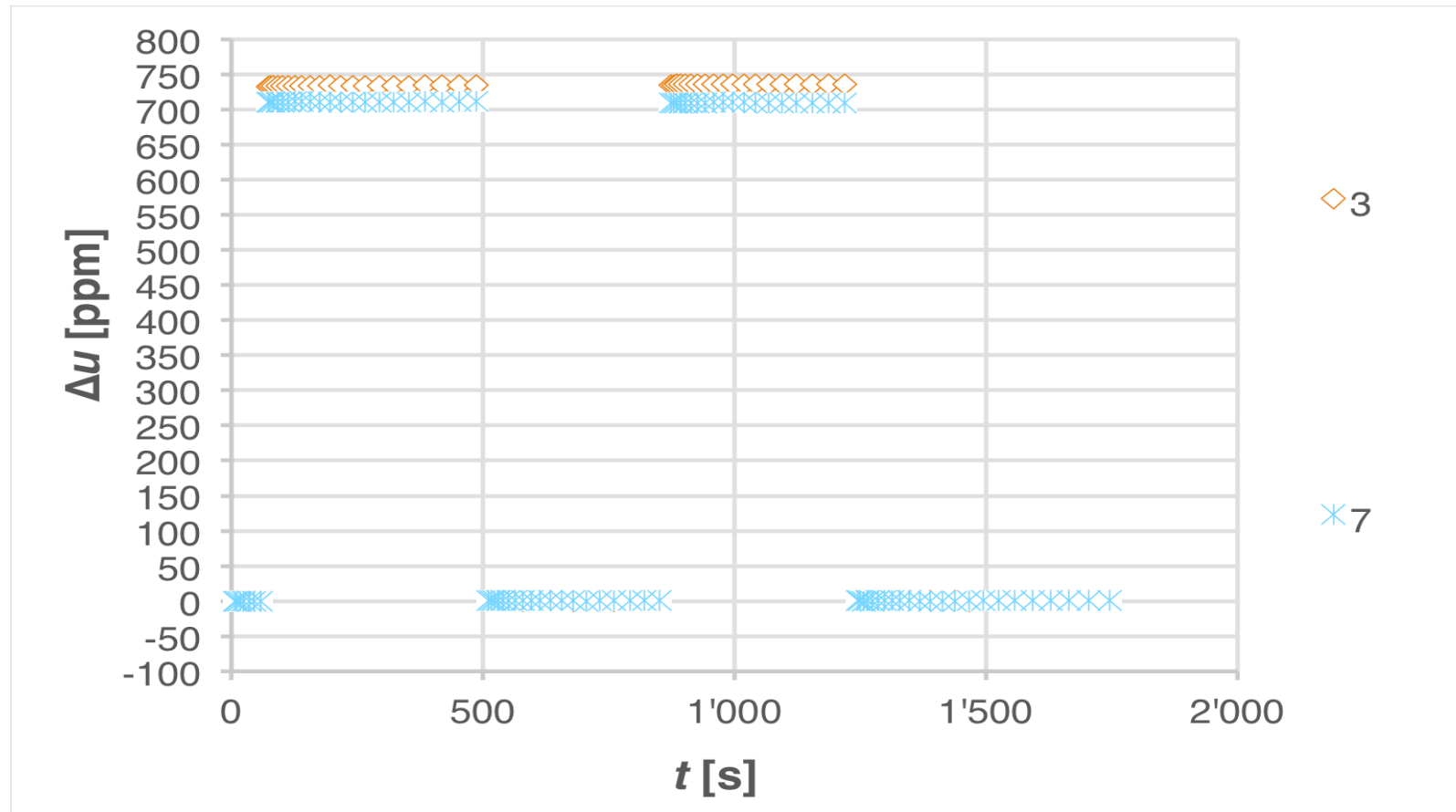
- High signal, large variations
- Visible zero drift (not anelastic) – damage ?
- No apparent dependence on layout

## H2 – 180 $\mu\text{m}$ LTCC HL2000 – layout 3



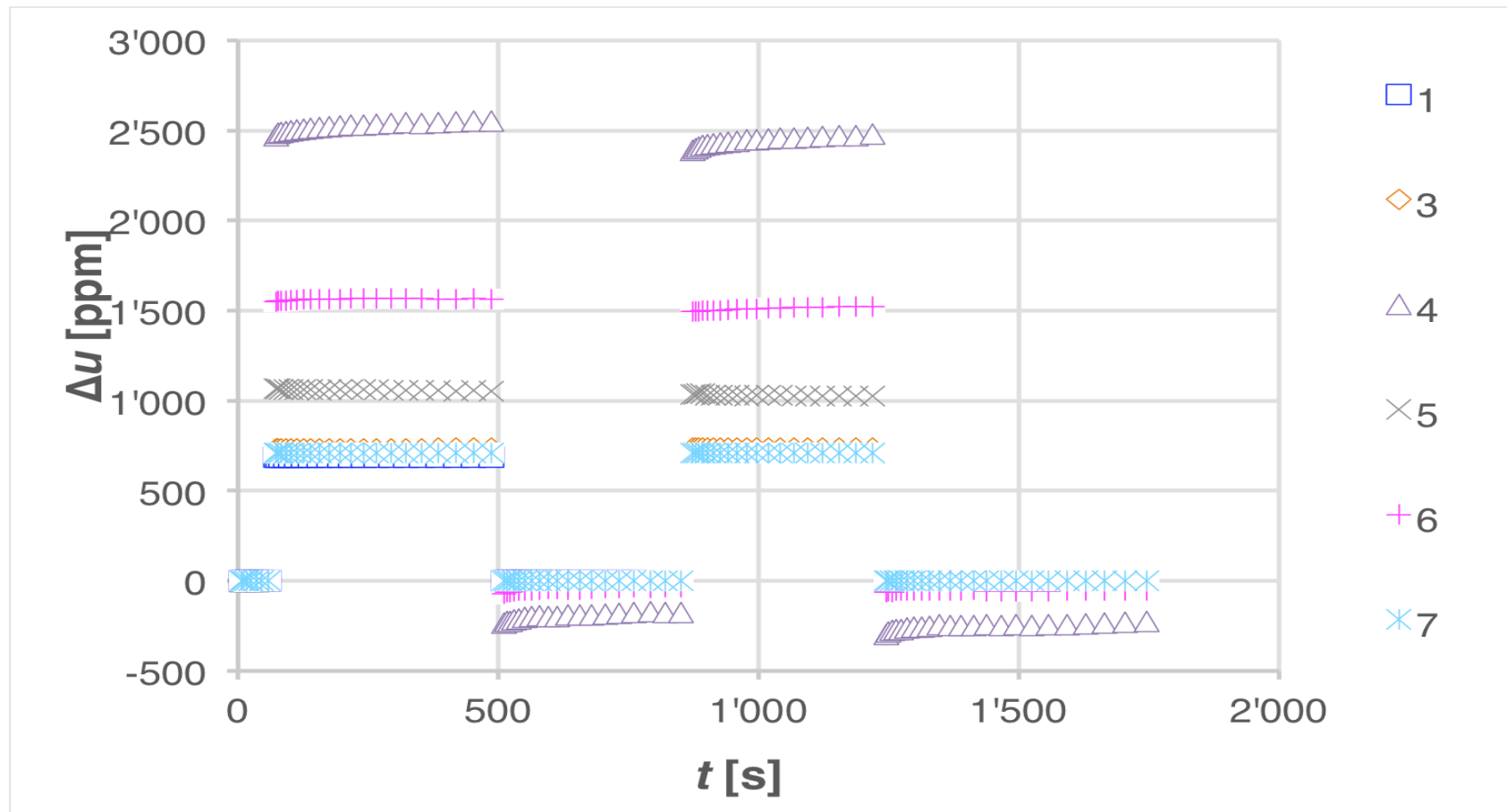
- High signal, large variations
- Visible zero drift (not anelastic) – damage ?
- No apparent dependence on layout

# H3 – 270 $\mu\text{m}$ LTCC HL2000 – layout 2



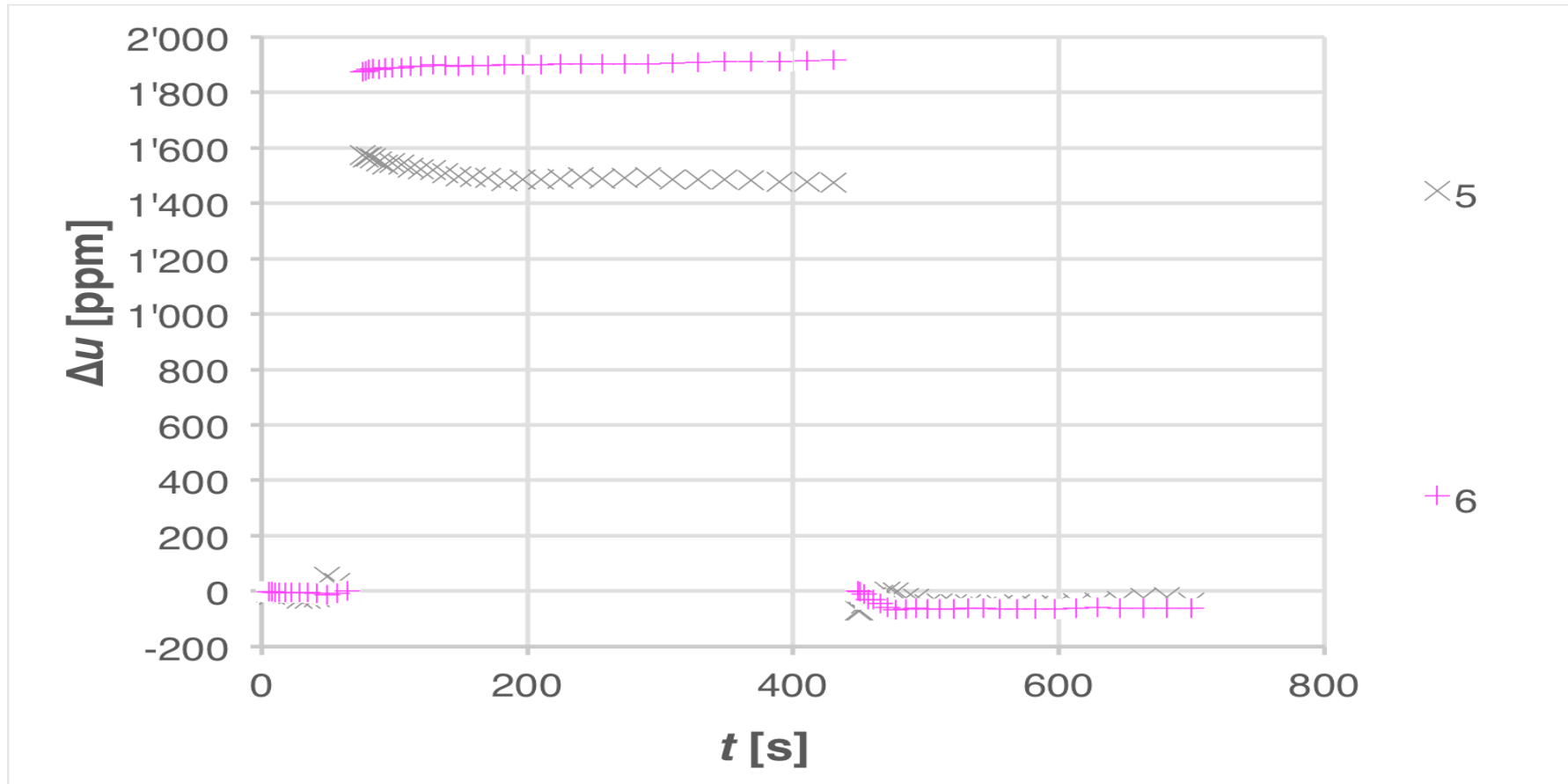
- Thicker: mostly similar behaviour
- Some "clean" samples

# H3 – 270 $\mu\text{m}$ LTCC HL2000 – layout 2



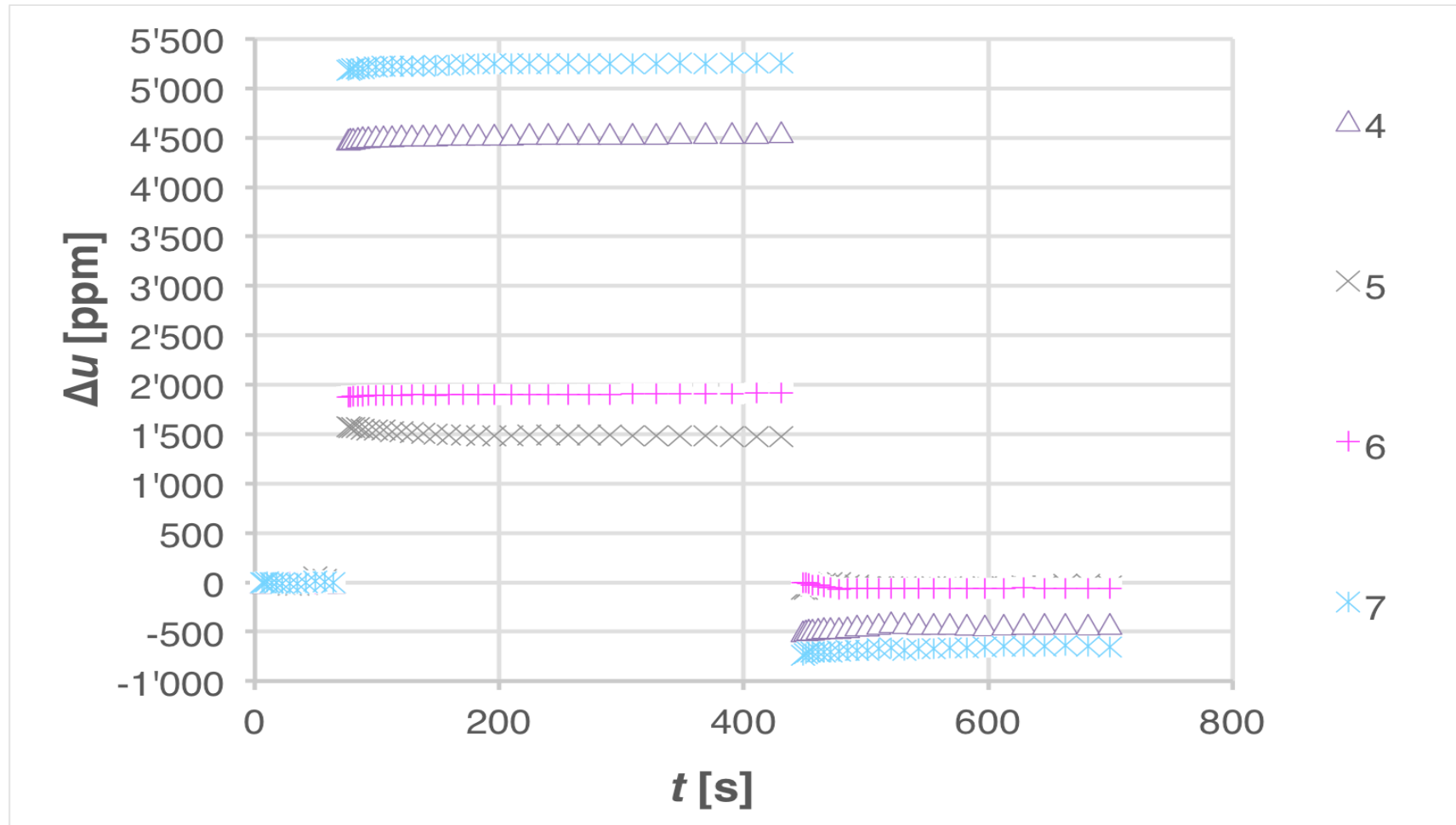
- Thicker: mostly similar behaviour
- Some "clean" samples

# I2 – 270 $\mu\text{m}$ LTCC DP951 – layout 2



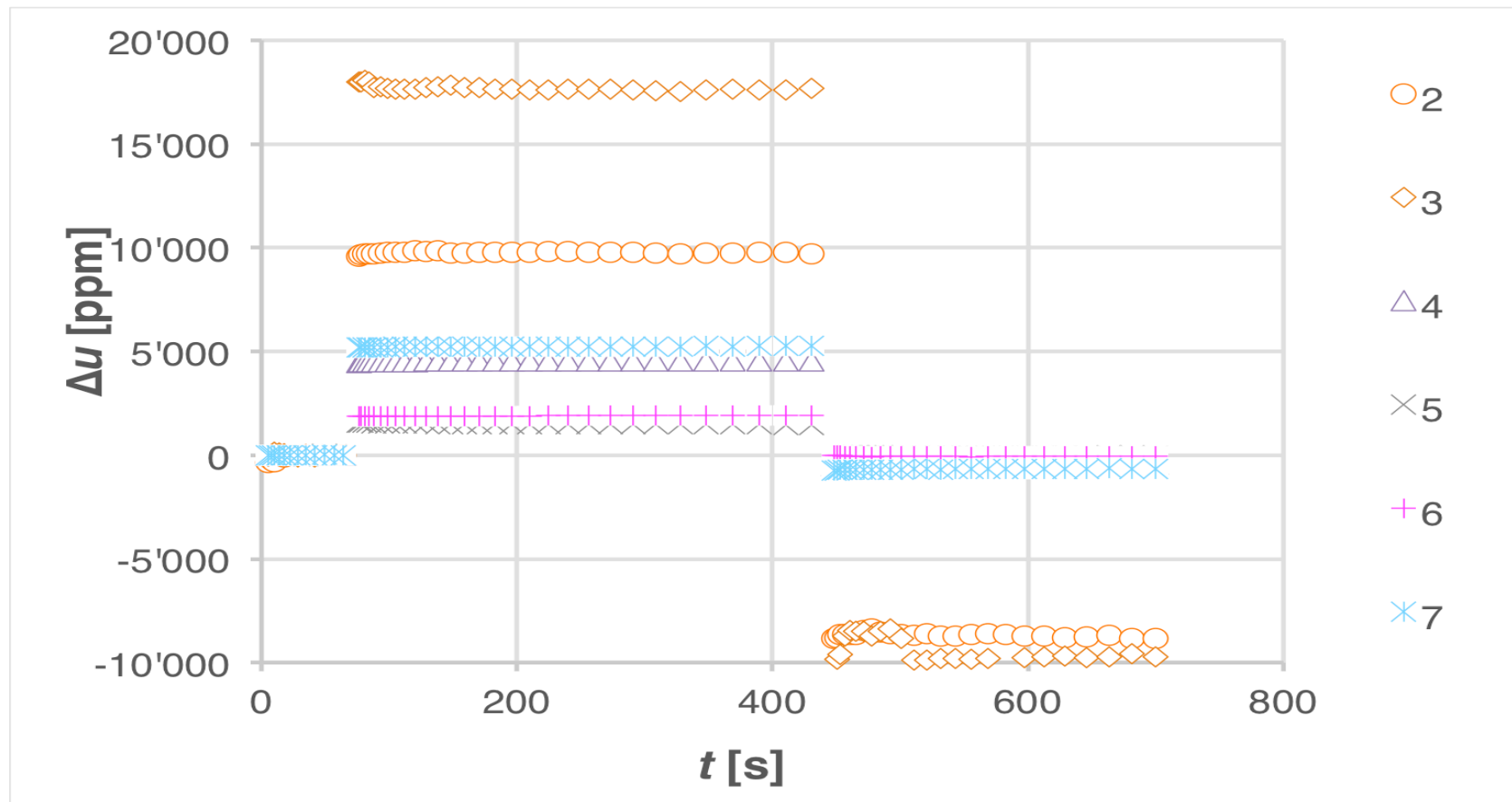
- Different LTCC : similar behaviour

# I2 – 270 $\mu\text{m}$ LTCC DP951 – layout 2



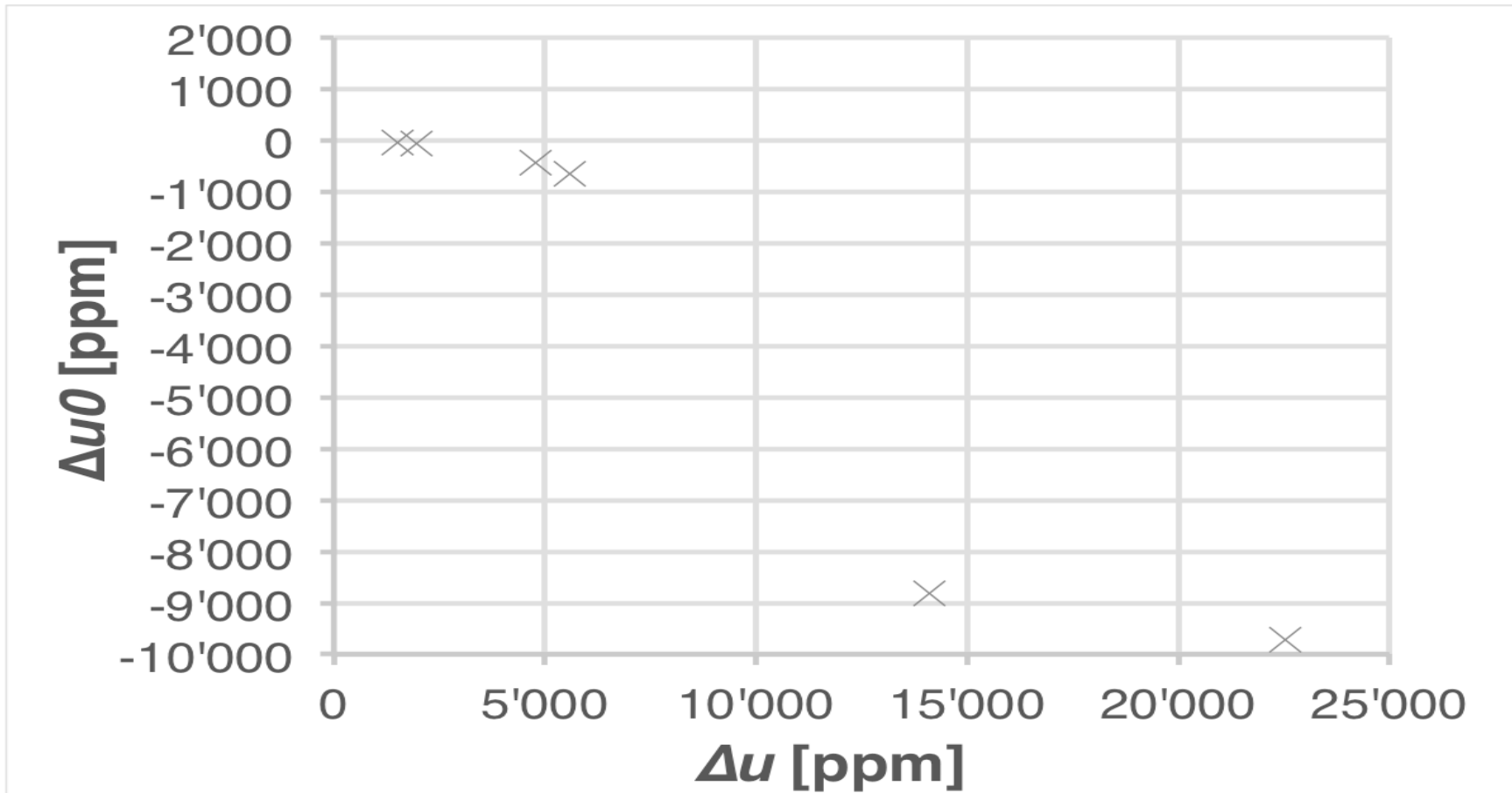
- Different LTCC : similar behaviour

# I2 – 270 $\mu\text{m}$ LTCC DP951 – layout 2



- Different LTCC : similar behaviour

# I2 – 270 $\mu\text{m}$ LTCC DP951 – layout 2



- Increase of drift with apparent signal -> anomalous



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# Conclusions

- Thin cantilevers on many substrates, including LTCC
- Same manufacturing process:
  - Post-fired, single-side
  - Two-layer, piezoresistors on thick-film dielectric
  - Resistors allowed above buried tracks (variant 3) or not (variant 2)
- Results:
  - $\text{Al}_2\text{O}_3$  / ZTA : clean signal, thermal drift not a problem
  - 3YSZ : possibly slight anelastic drift & thermal effects due to very low thermal conductance of cantilever
  - LTCC : signal mostly unstable (some clean samples)
    - **Cause ? Low thermal expansion ?**

- Elucidate drift mechanism on LTCC
  - Perform progressive loading tests
  - Check for resistor damage
  - Try on LTCC with high CTE – should avoid instabilities
- Extended analysis of new design
  - Performance & economics vs existing cantilever
  - Sensitivity to side loads
  - Lowest practical force ranges (deflection, manufacturing...)

# The end

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*Thank you for your attention !*

